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Lim et al.

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(54) **SEMICONDUCTOR DEVICE AND APPARATUS OF MANUFACTURING THE SAME**

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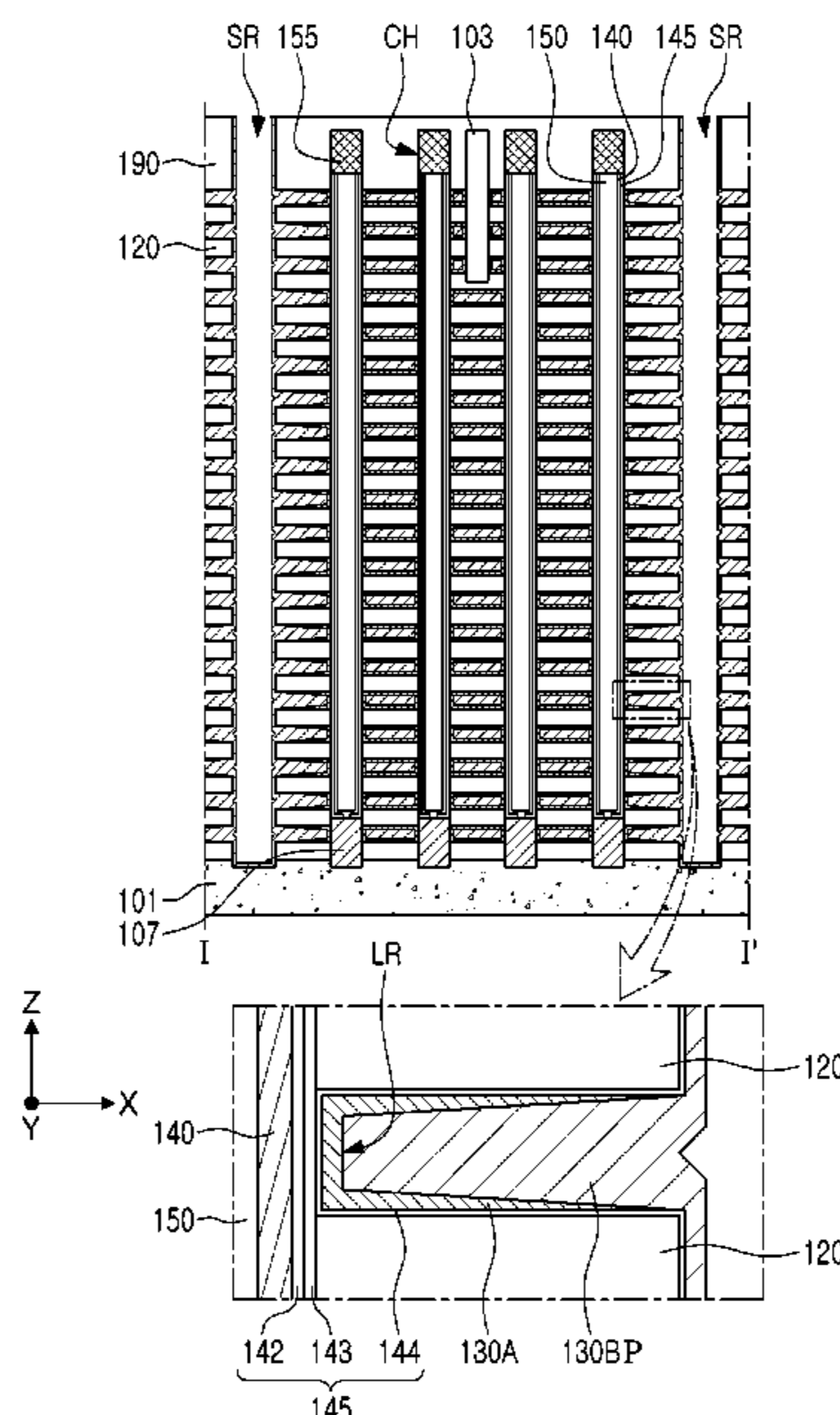
Primary Examiner — Thanhha S Pham

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(57) **ABSTRACT**

A semiconductor device includes gate electrodes and interlayer insulating layers that are alternately stacked on a substrate, channel structures spaced apart from each other in a first direction and extending vertically through the gate electrodes and the interlayer insulating layers to the substrate, and a first separation region extending vertically through the gate electrodes and the interlayer insulating layers. Each gate electrode includes a first conductive layer and a second conductive layer, the first conductive layer disposed between the second conductive layer and each of two adjacent interlayer insulating layers. In a first region, between an outermost channel structure and the first separation region, of each gate electrode, the first conductive layer has a decreasing thickness toward the first separation region and the second conductive layer has an increasing thickness toward the first separation region.

20 Claims, 22 Drawing Sheets



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H10B 43/40 (2023.01)
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H01L 21/285 (2006.01)
H01L 21/3213 (2006.01)
C23C 16/56 (2006.01)
C23C 16/455 (2006.01)
C23C 16/06 (2006.01)
H01L 21/28 (2006.01)
H01L 21/02 (2006.01)
H01L 29/66 (2006.01)

- (52) **U.S. Cl.**
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 (2019.08); *H01L 29/4234* (2013.01); *H10B*
43/10 (2023.02); *H10B 43/40* (2023.02); *H01L*
21/02636 (2013.01); *H01L 21/67167*
 (2013.01); *H01L 29/66545* (2013.01)

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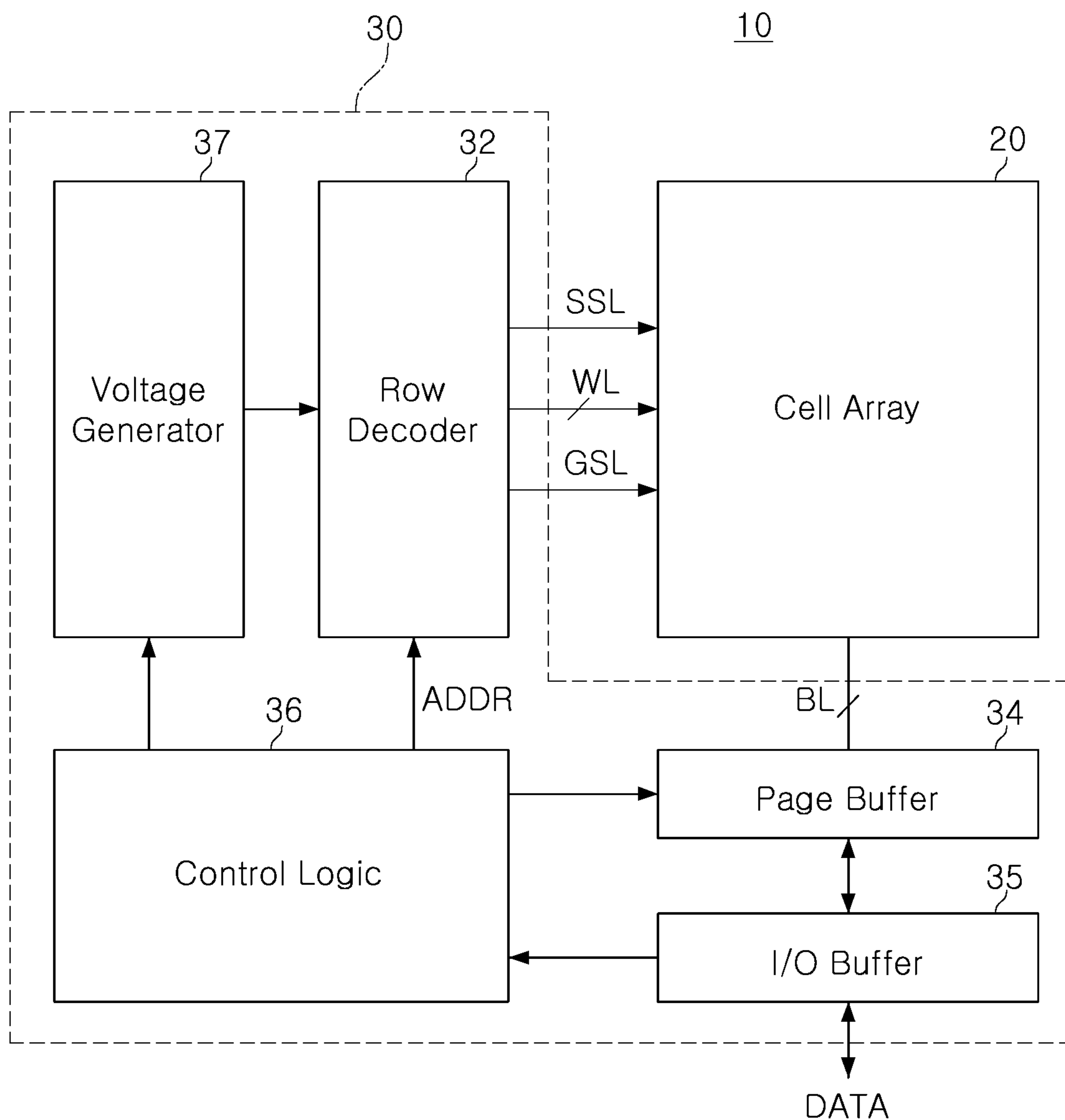


FIG. 1

20

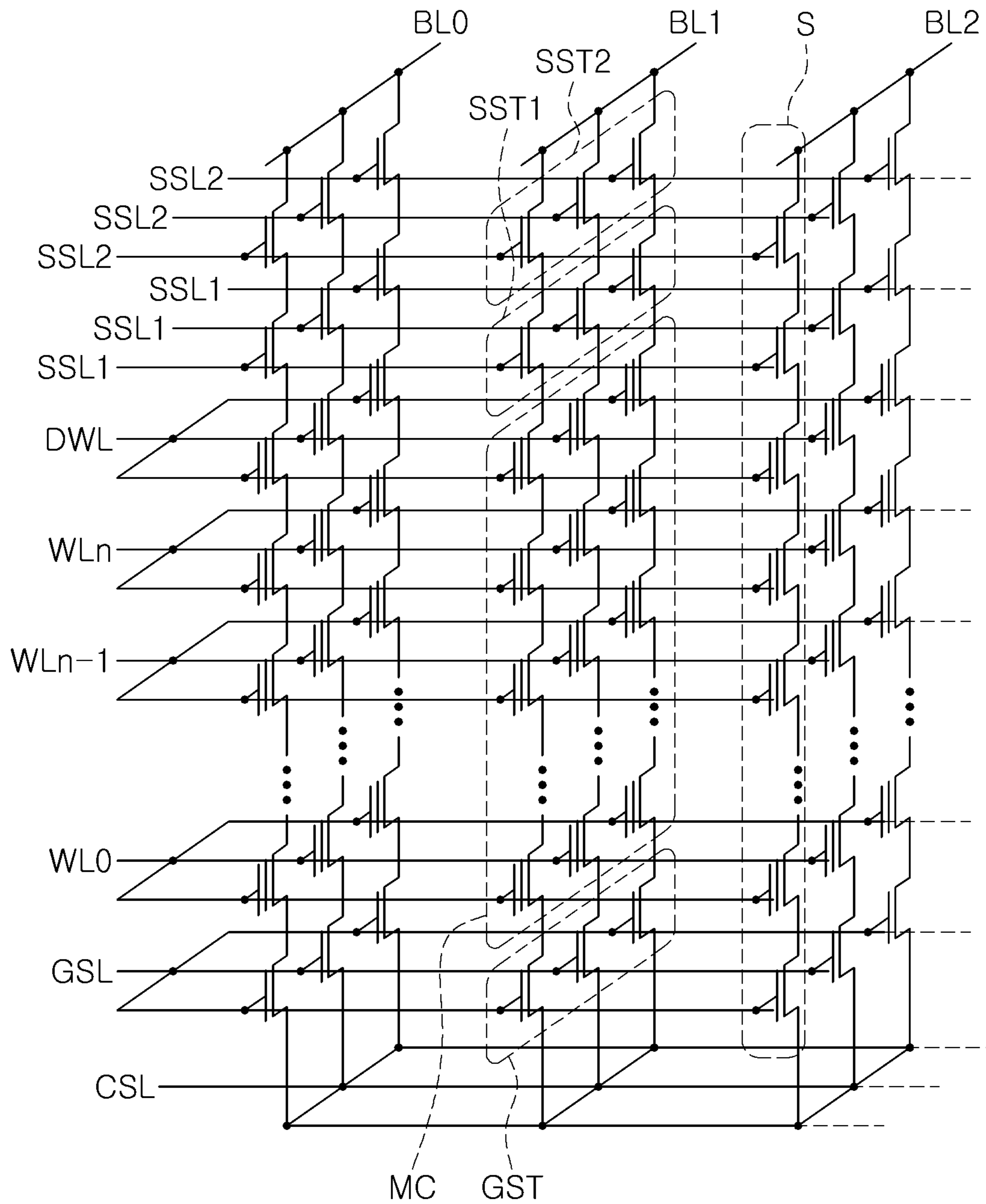


FIG. 2

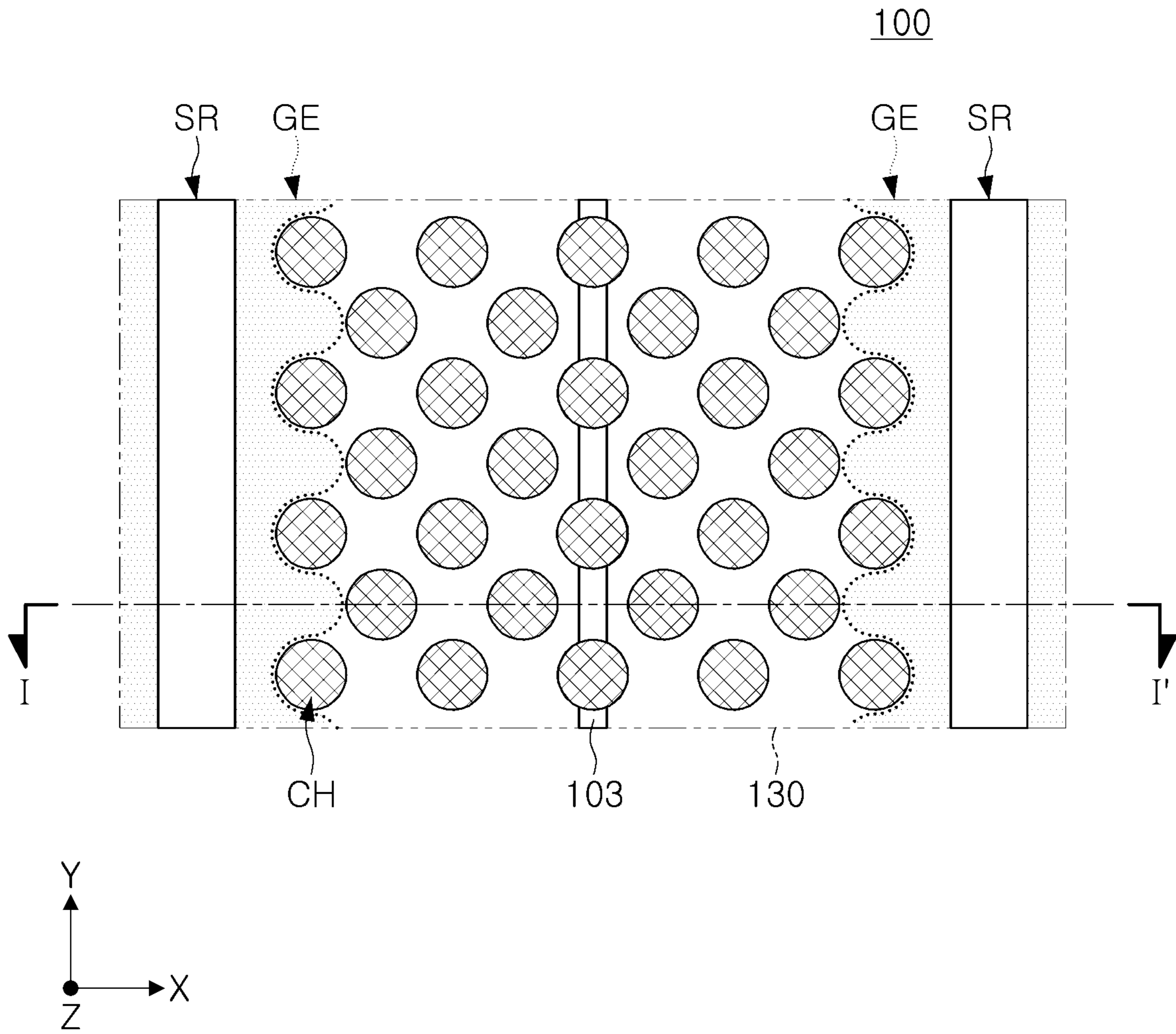


FIG. 3

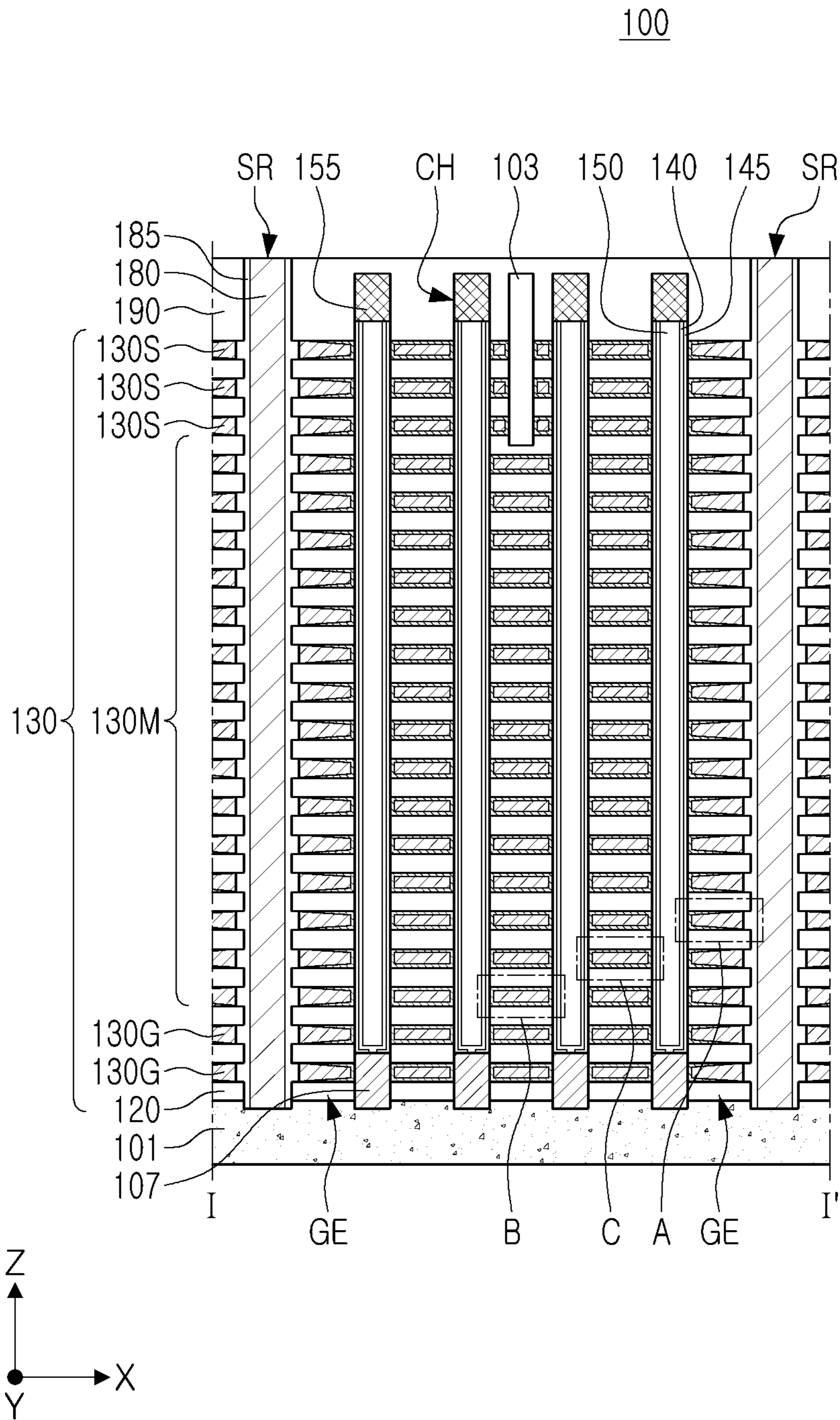
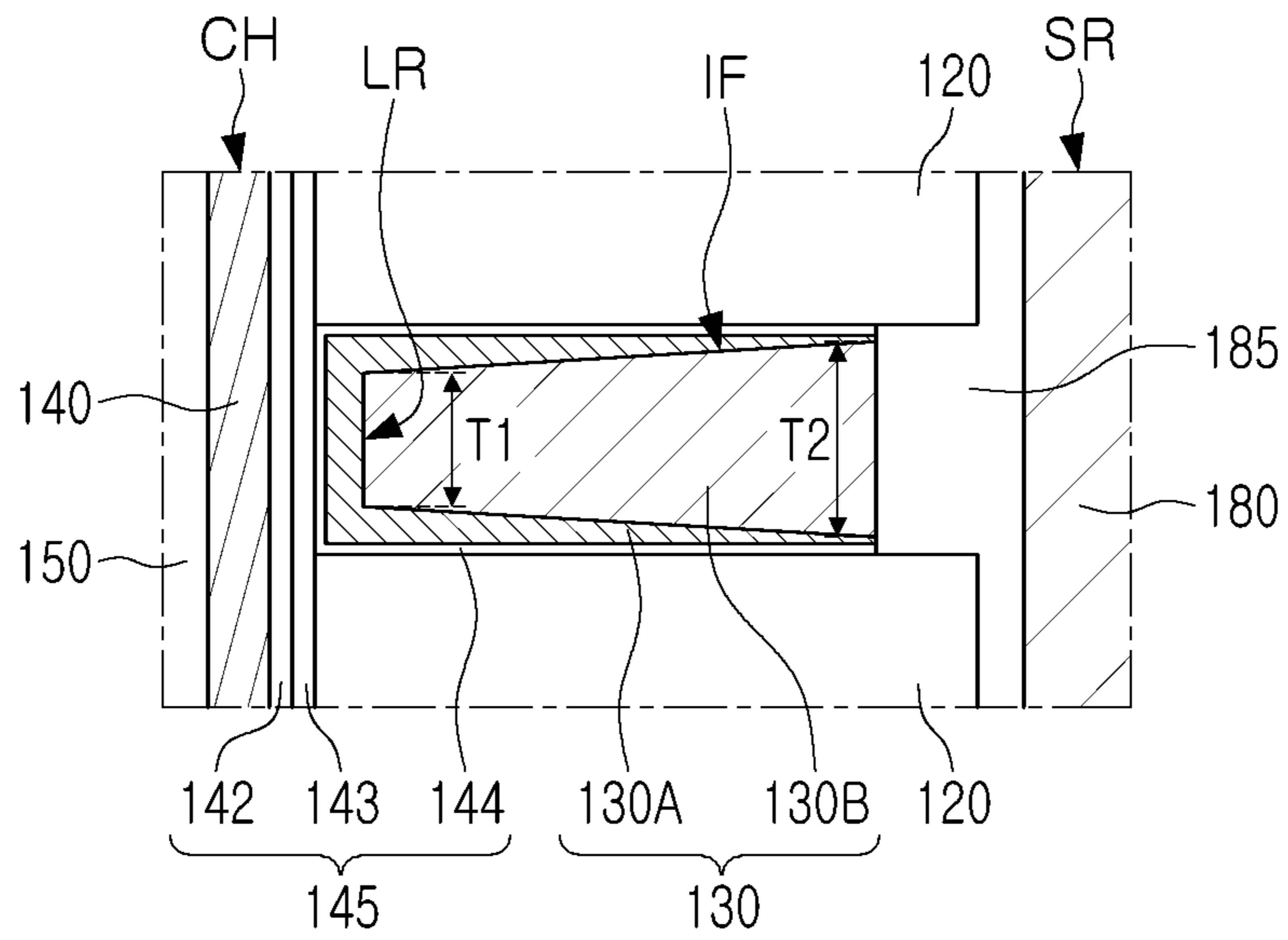
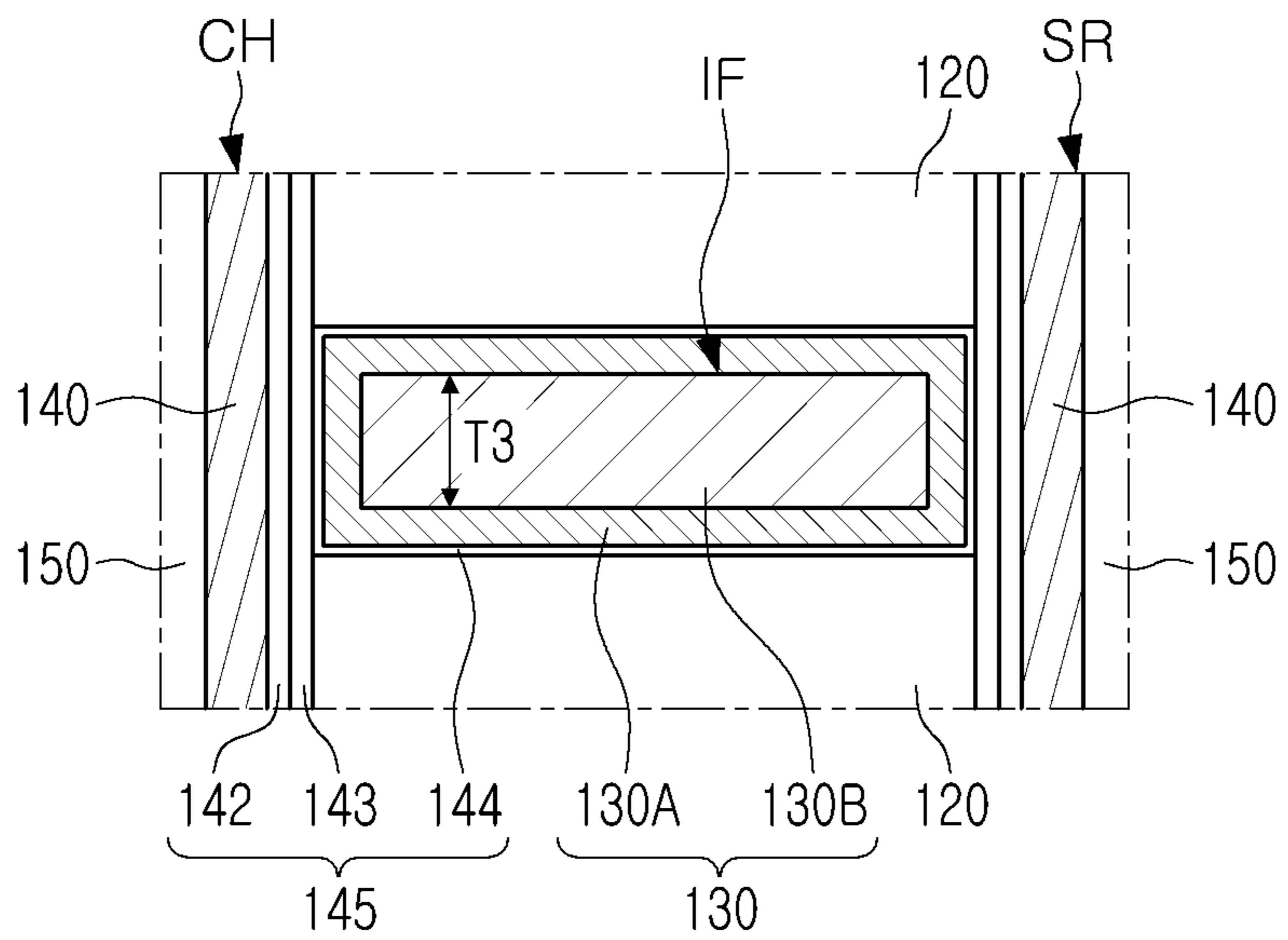


FIG. 4



A

FIG. 5A



B

FIG. 5B

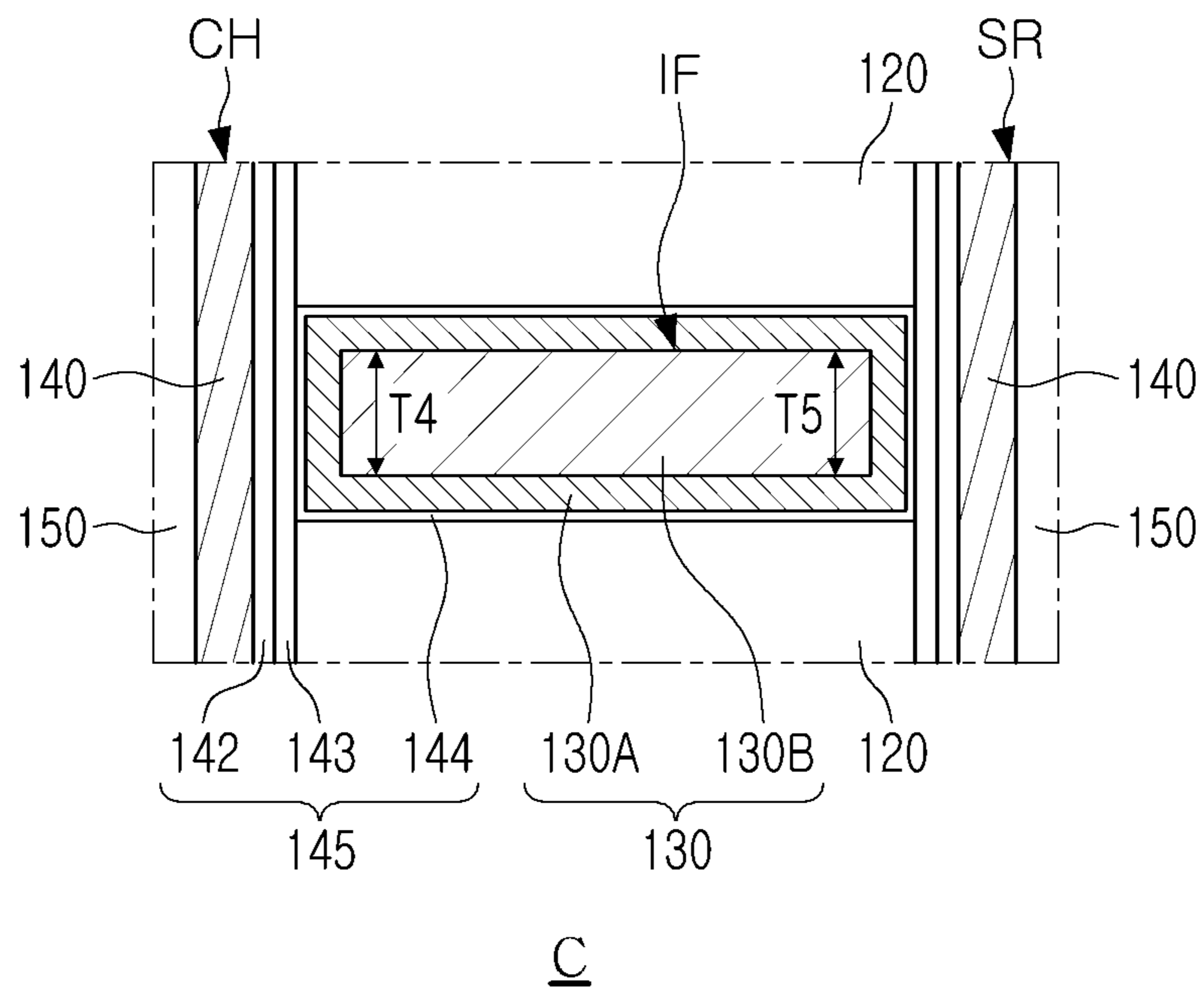


FIG. 5C

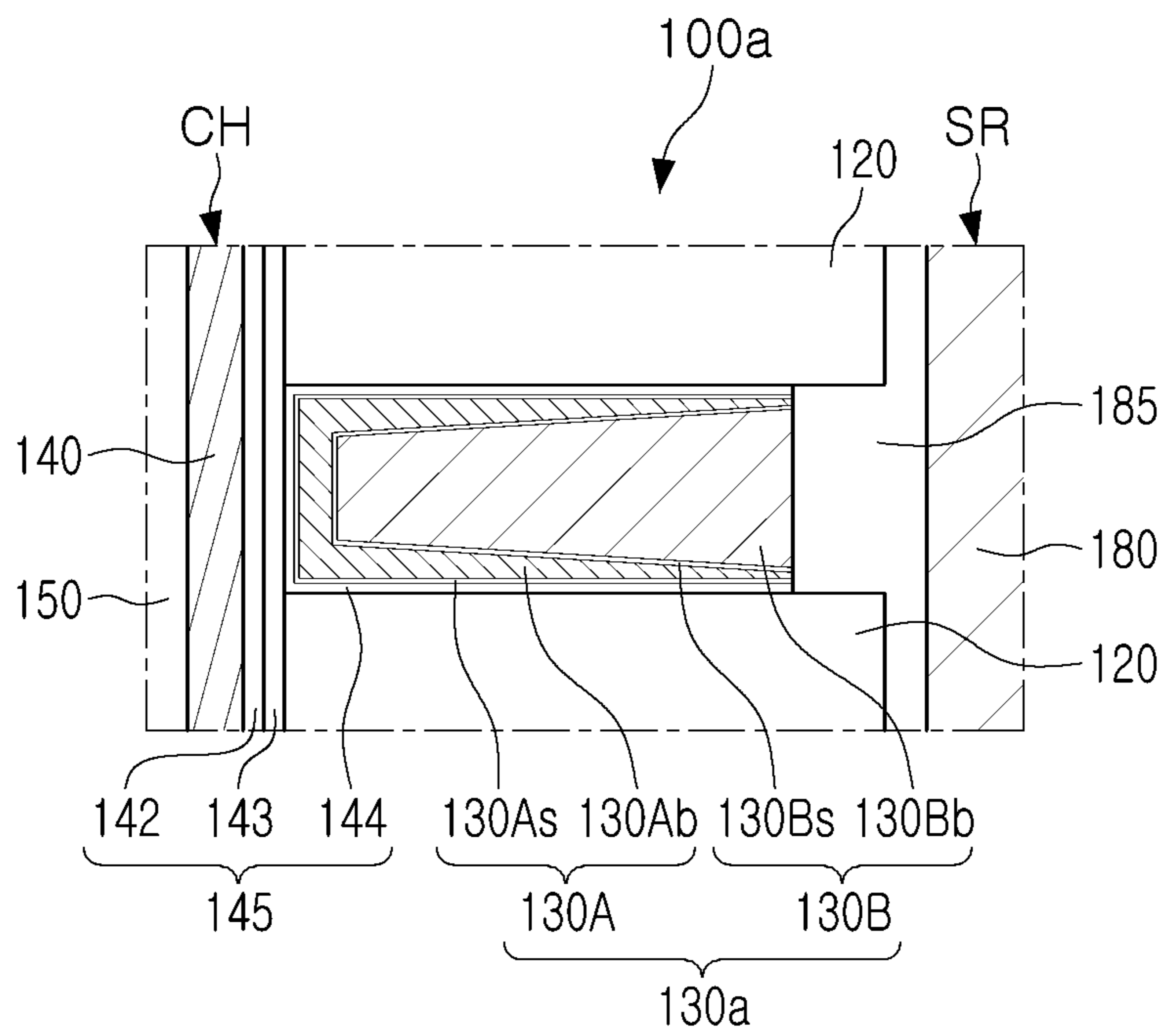


FIG. 6A

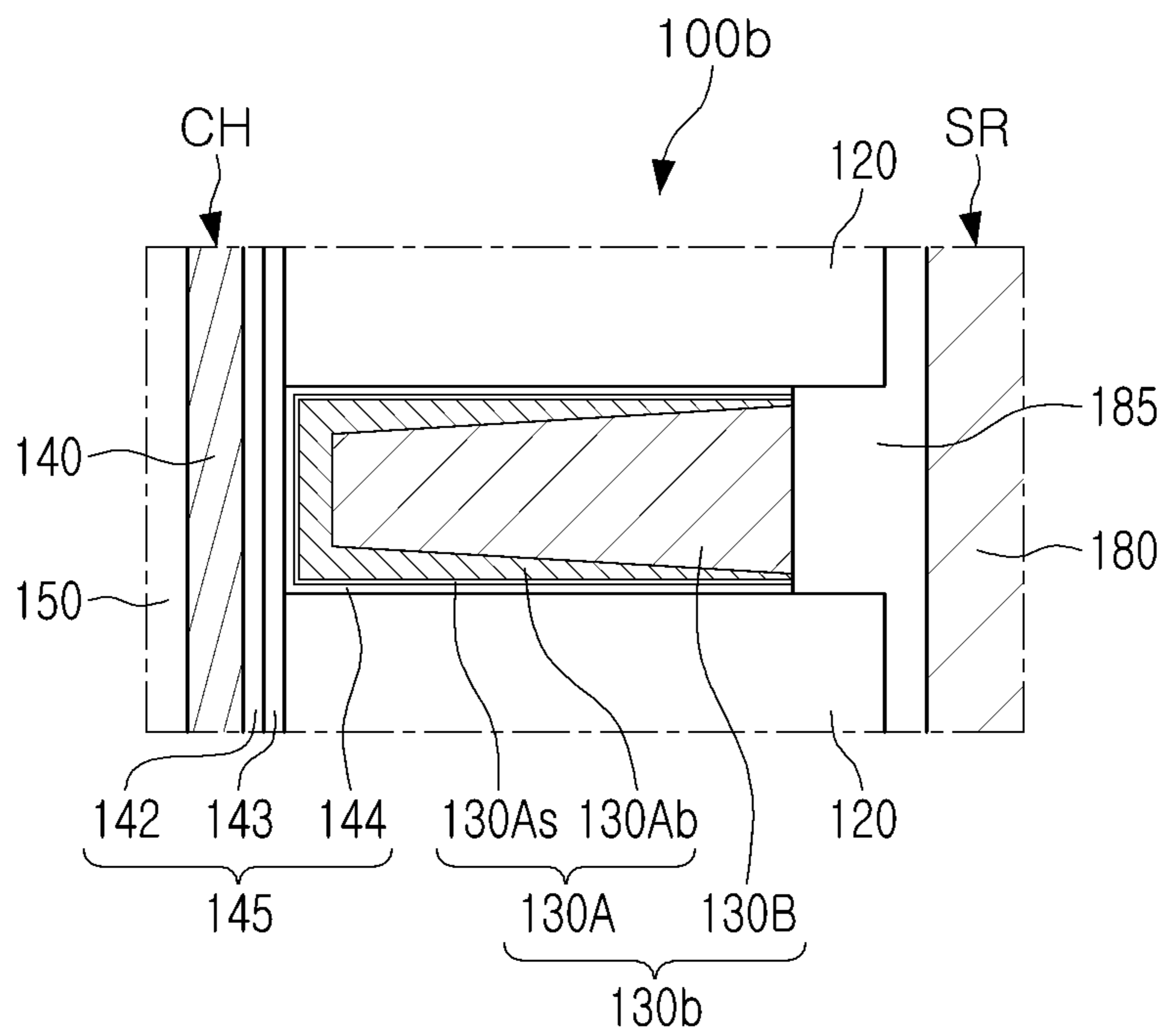


FIG. 6B

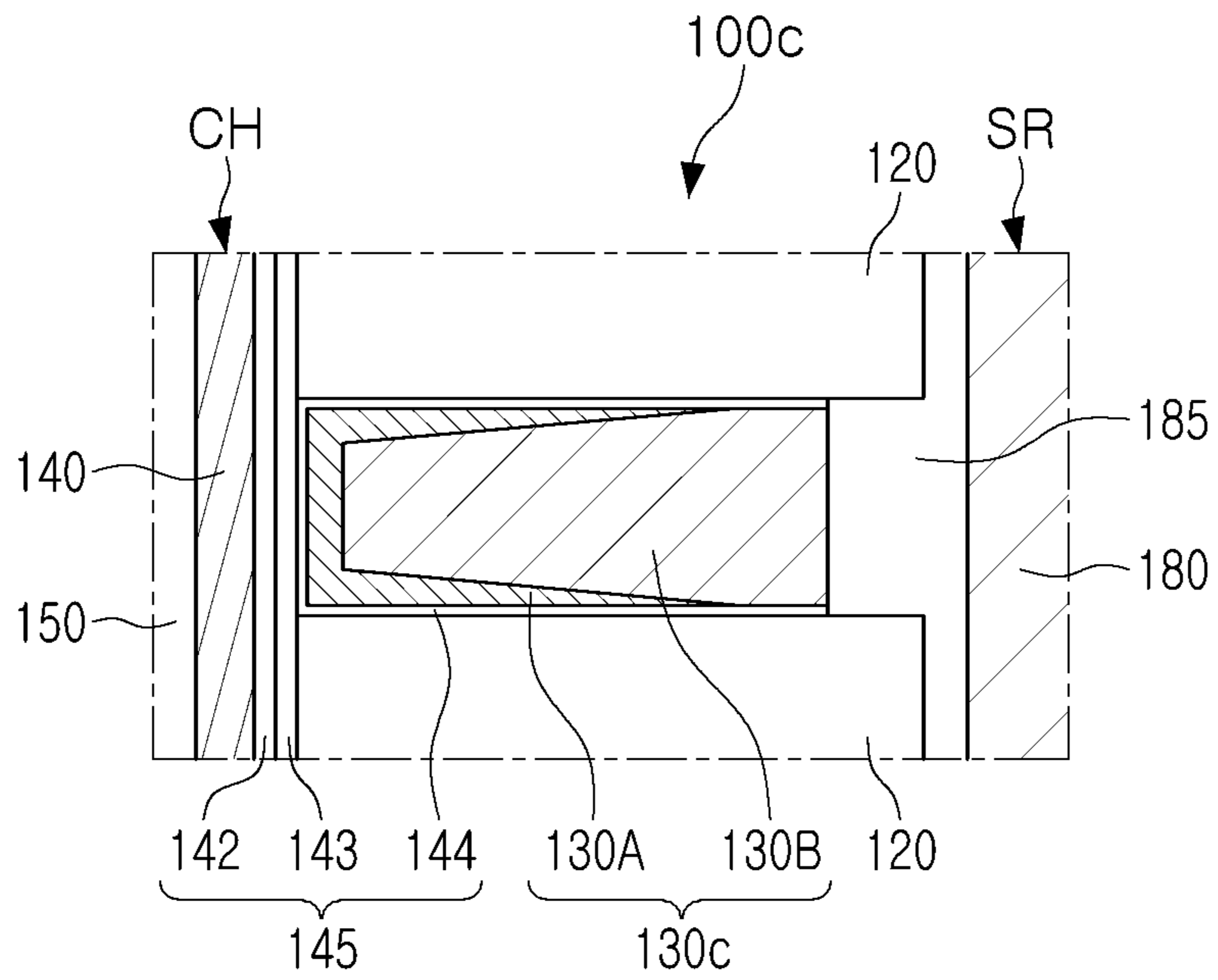


FIG. 7

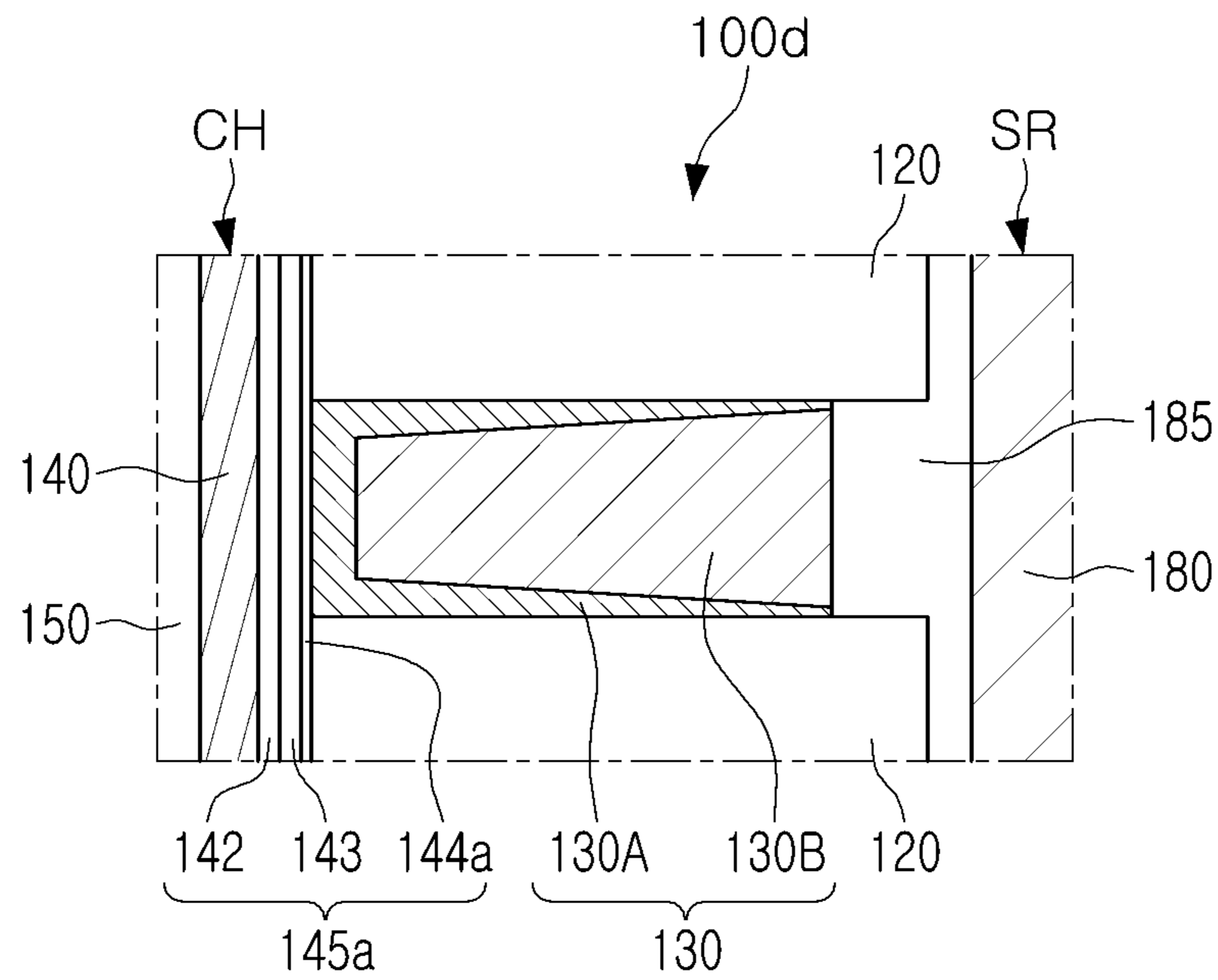


FIG. 8

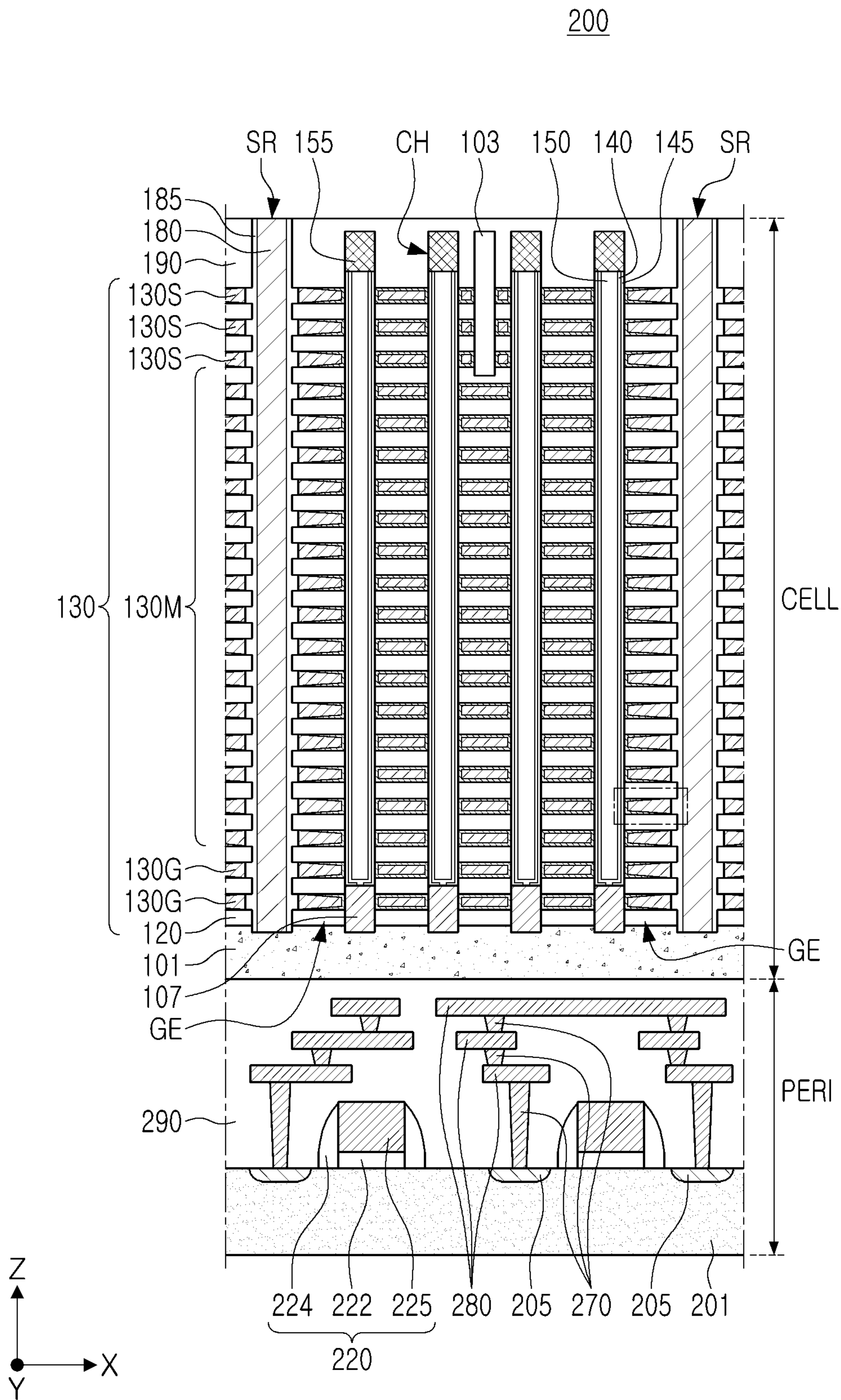


FIG. 9

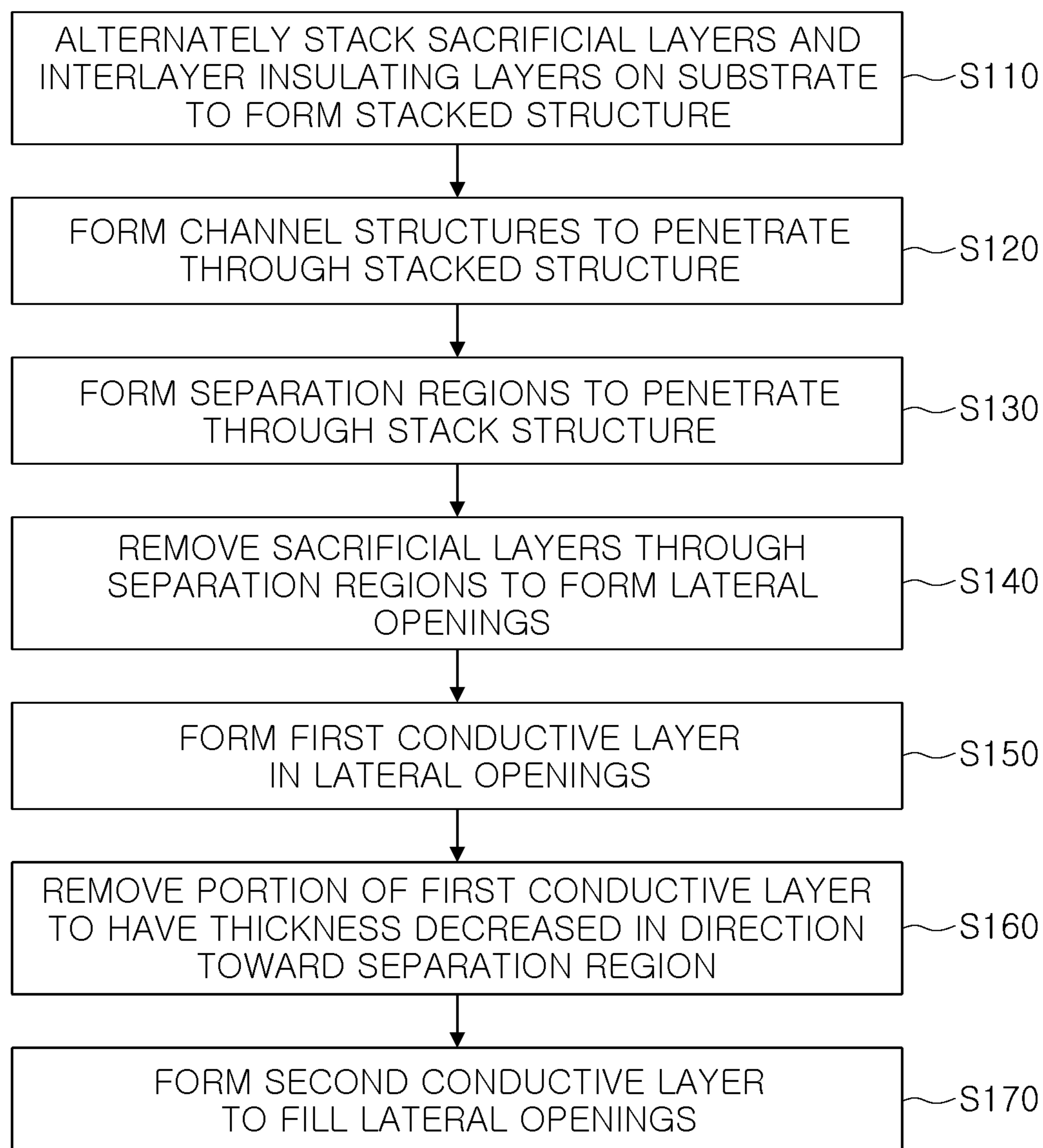


FIG. 10

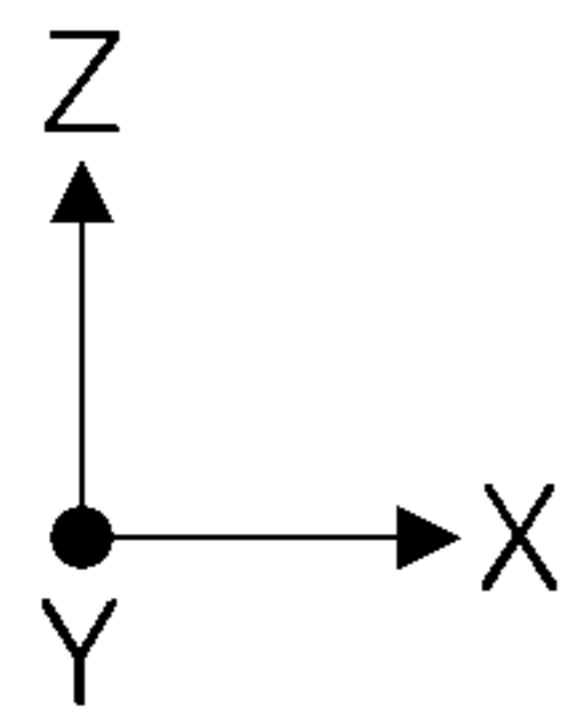
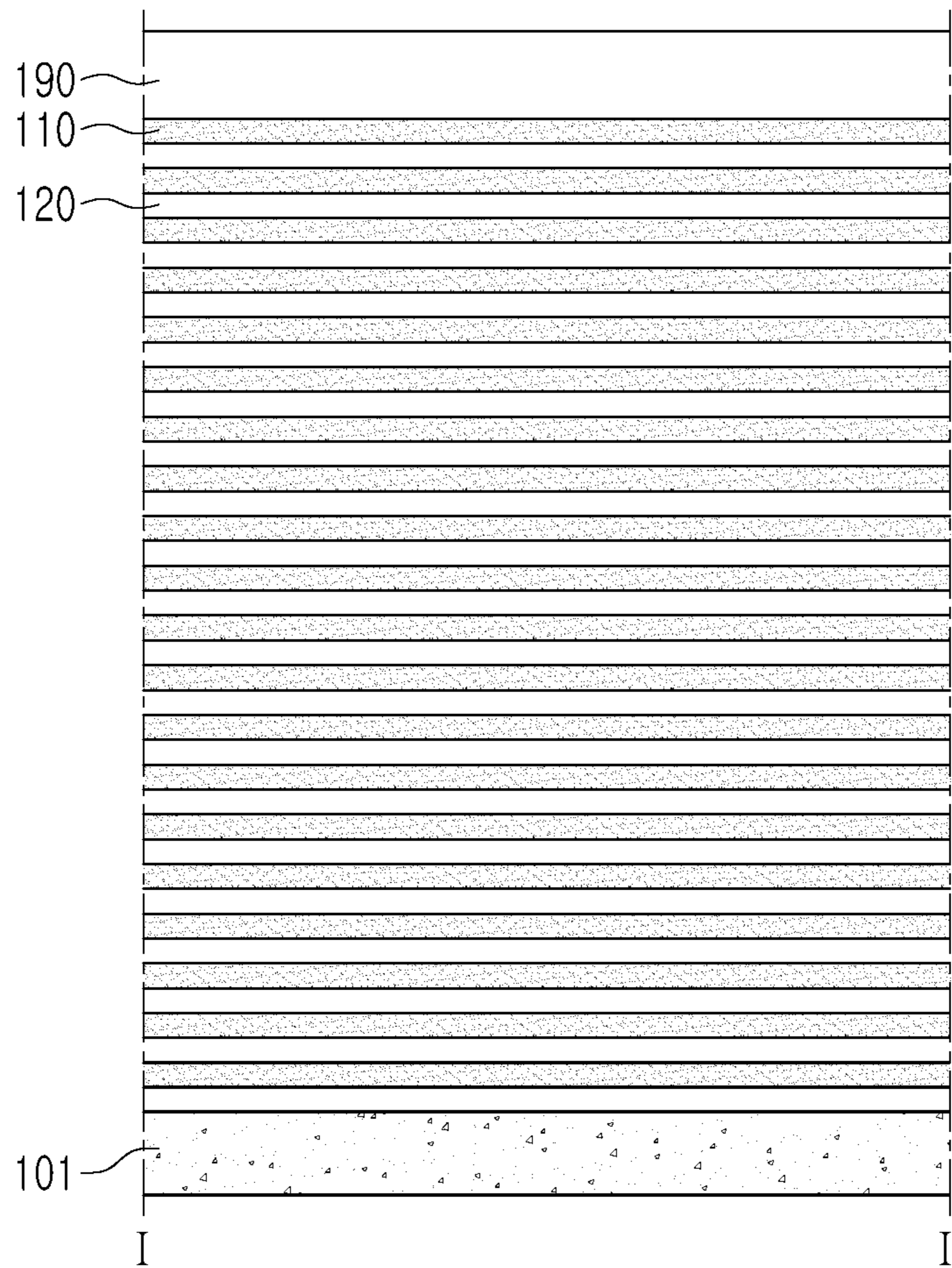


FIG. 11A

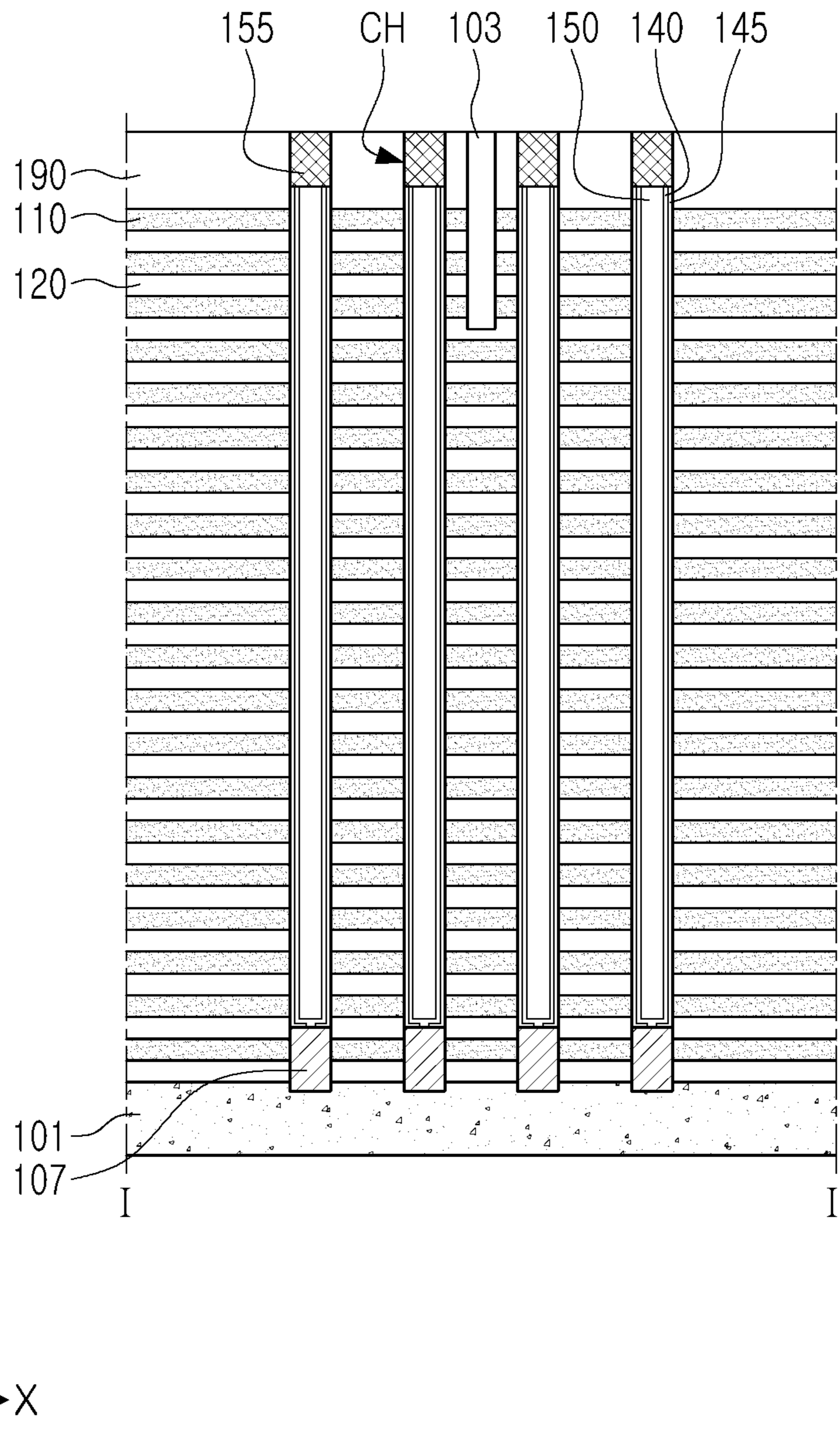


FIG. 11B

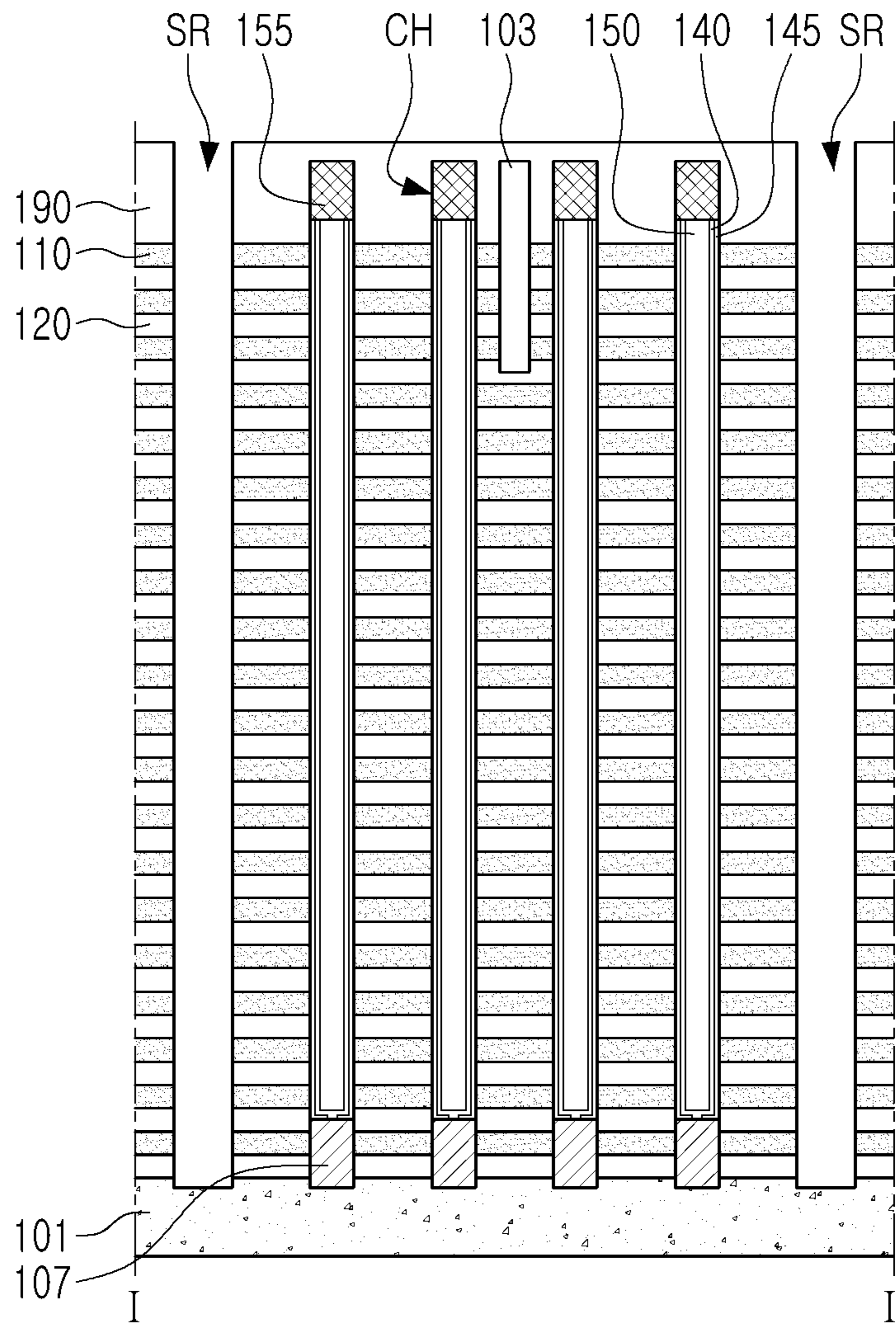


FIG. 11C

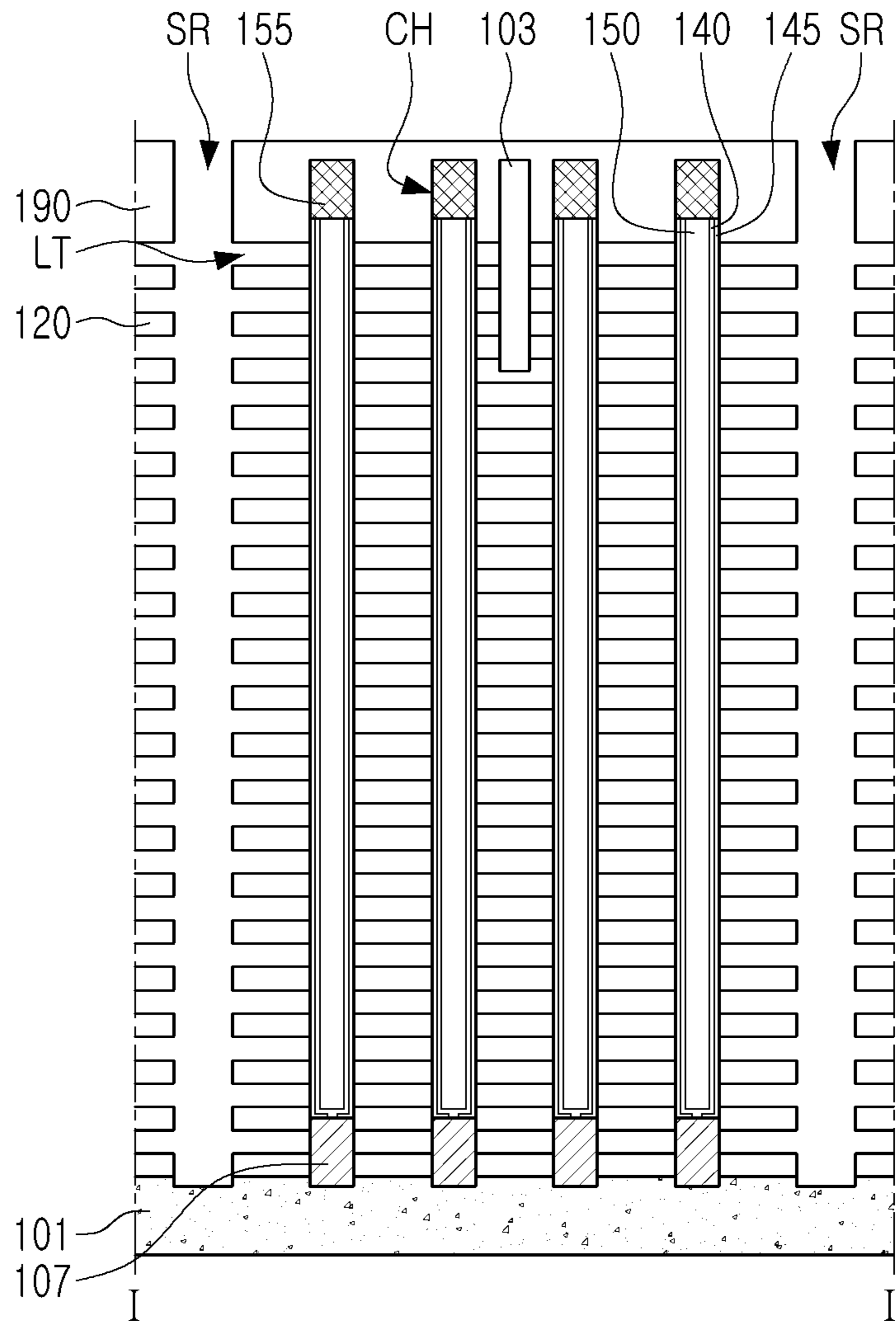


FIG. 11D

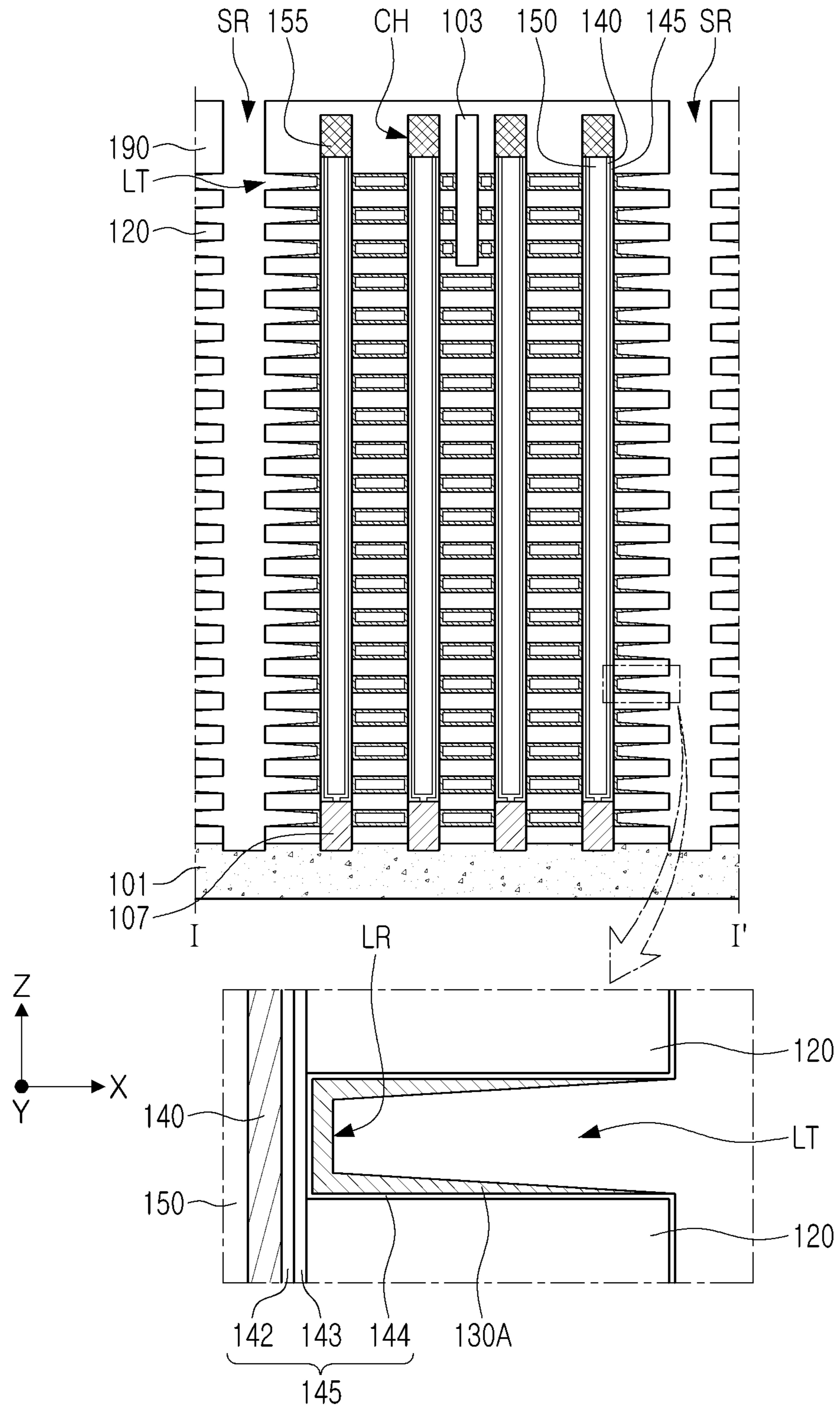


FIG. 11F

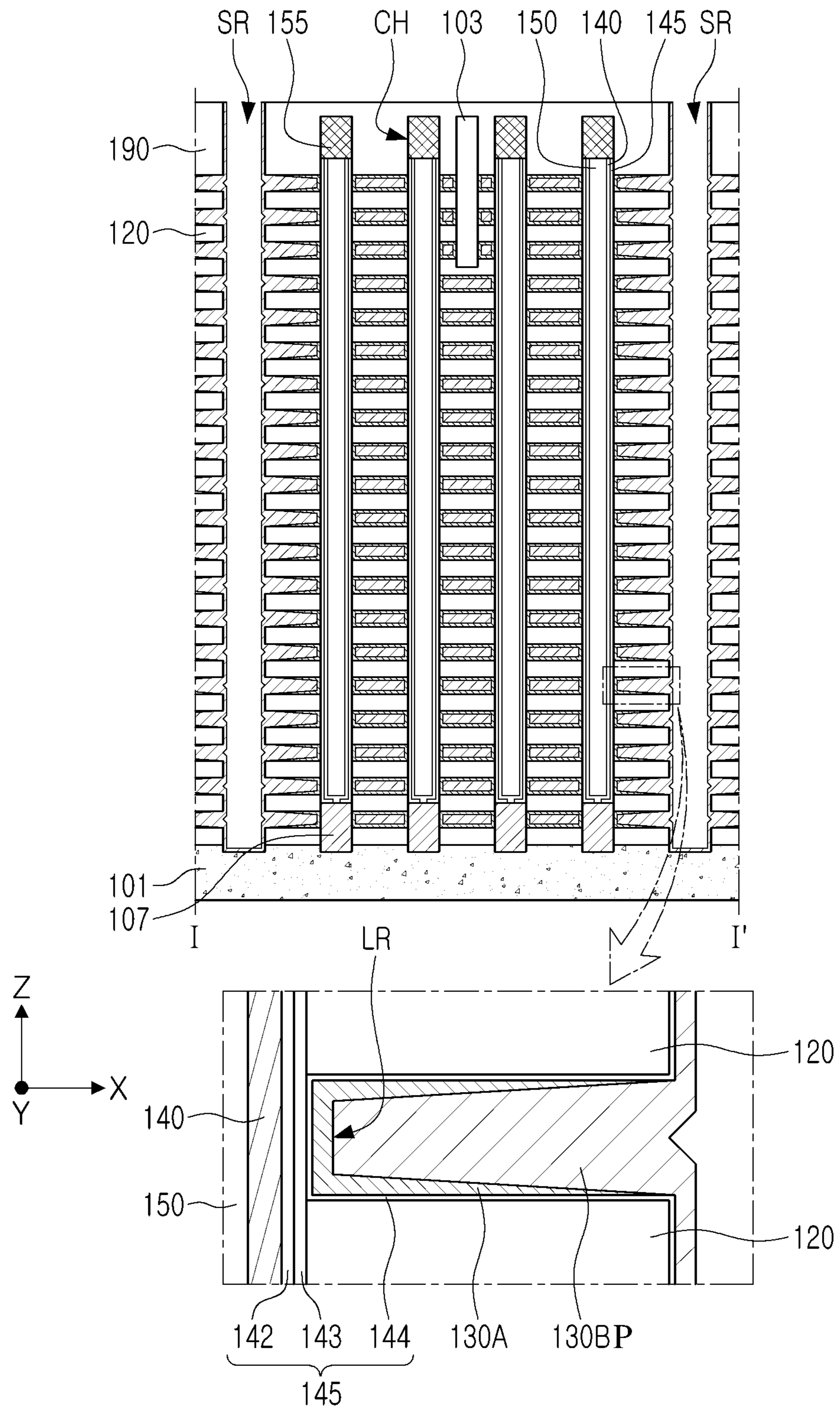


FIG. 11G

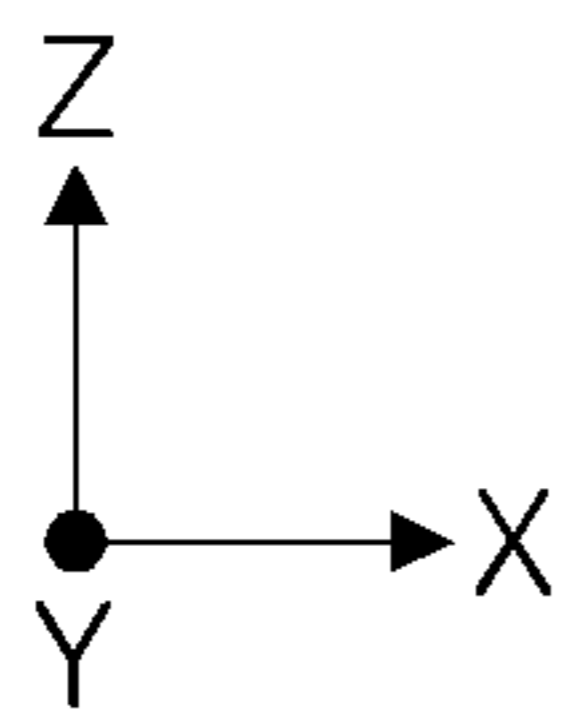
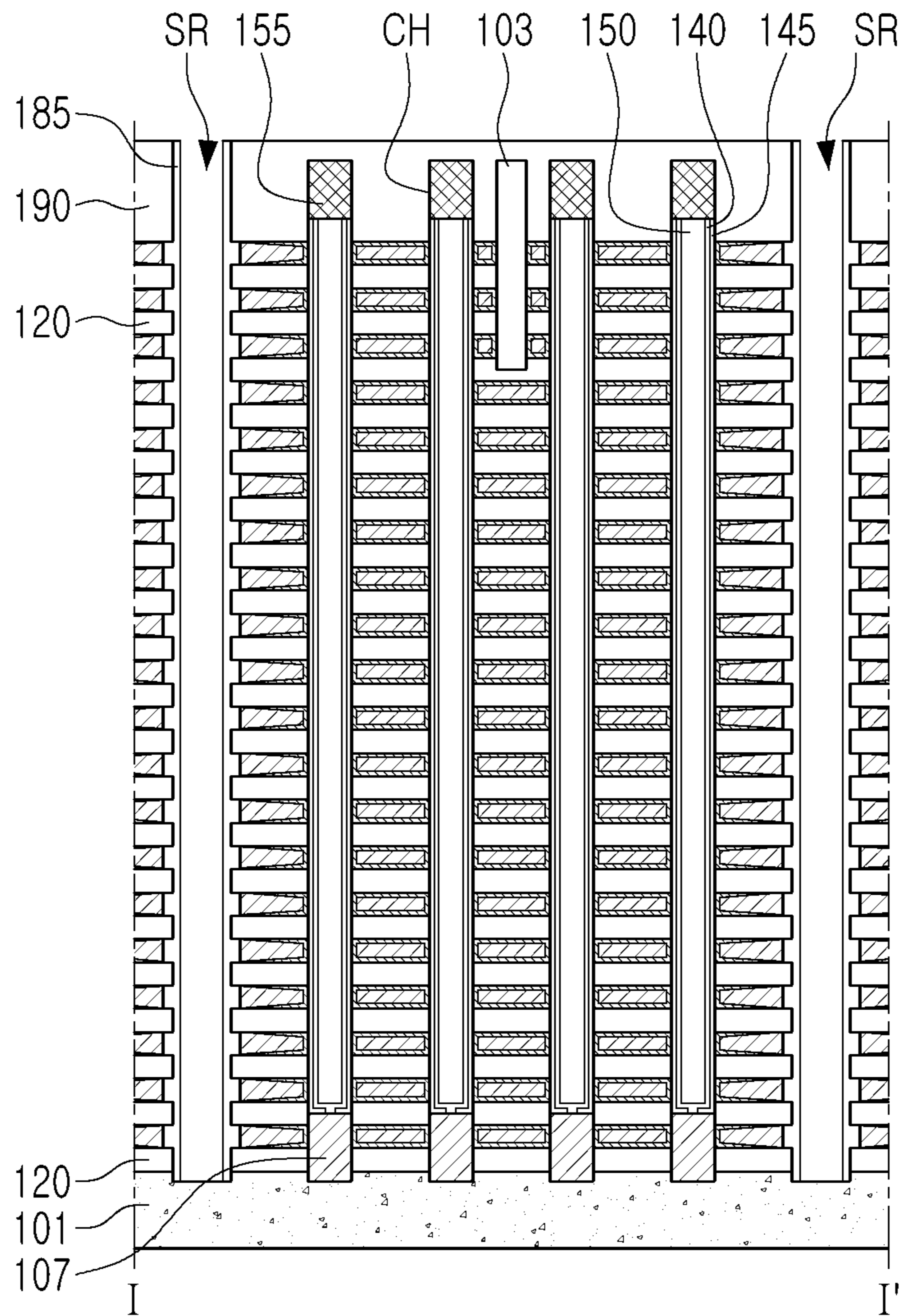


FIG. 11I

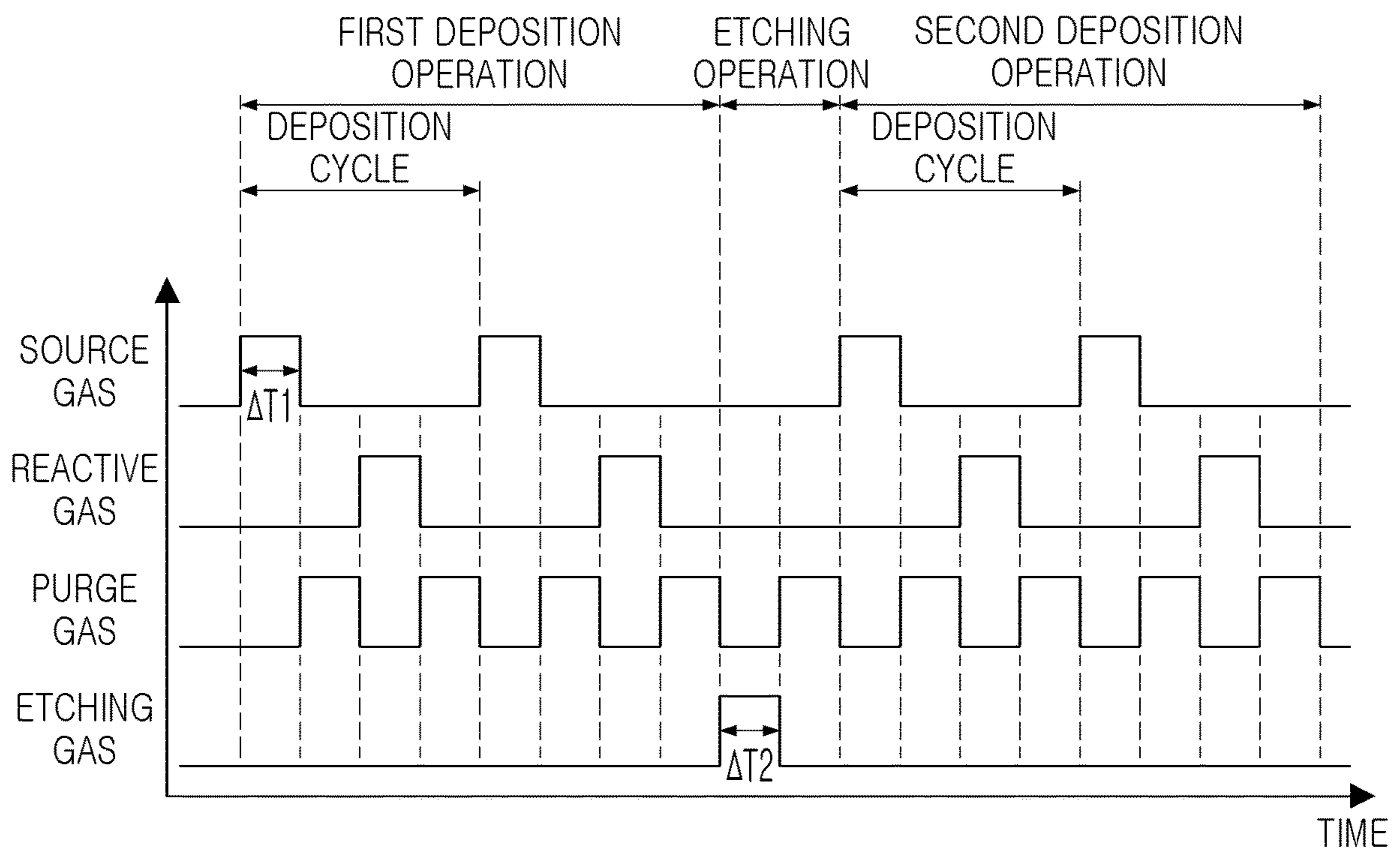


FIG. 12

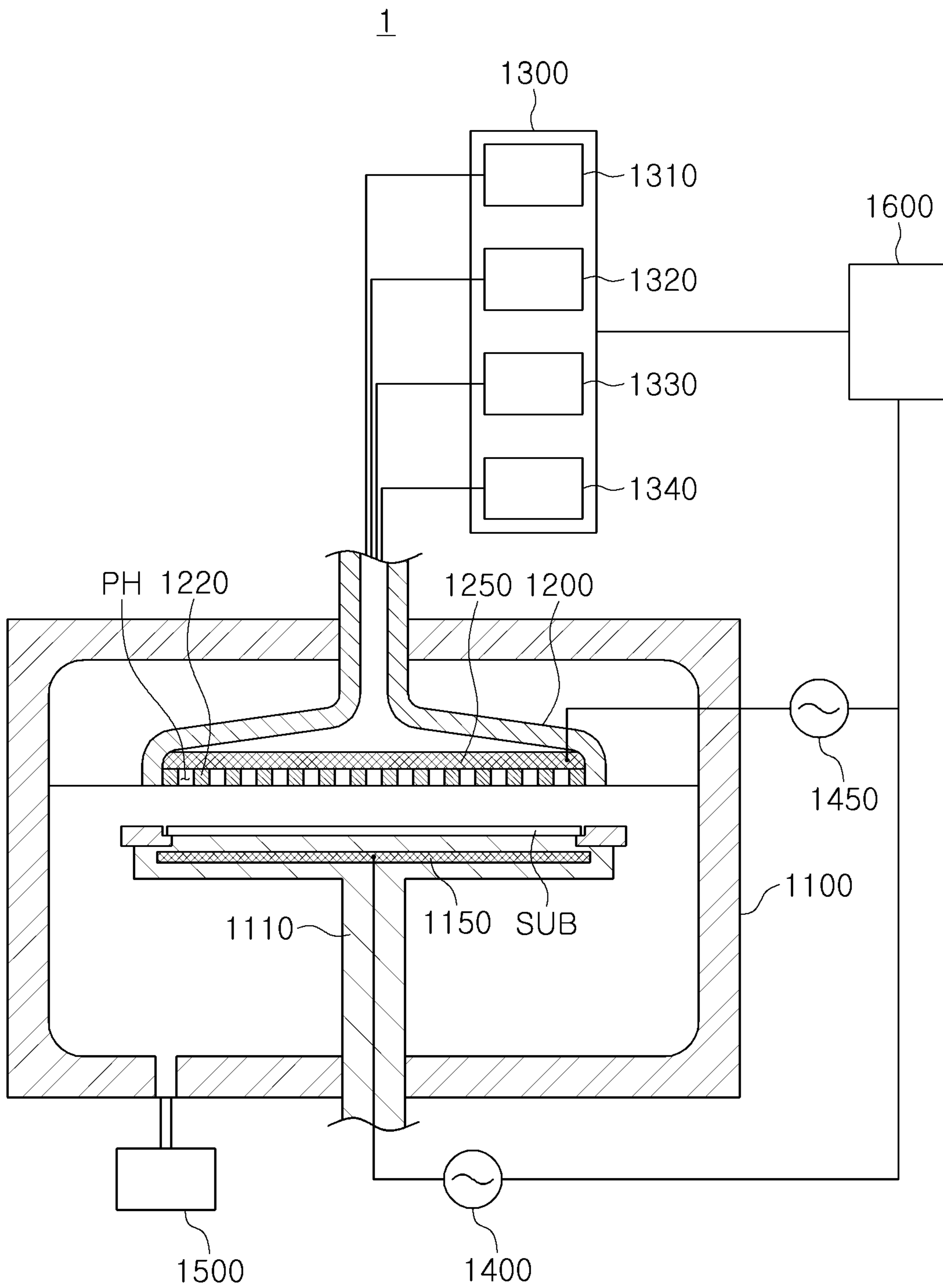


FIG. 13

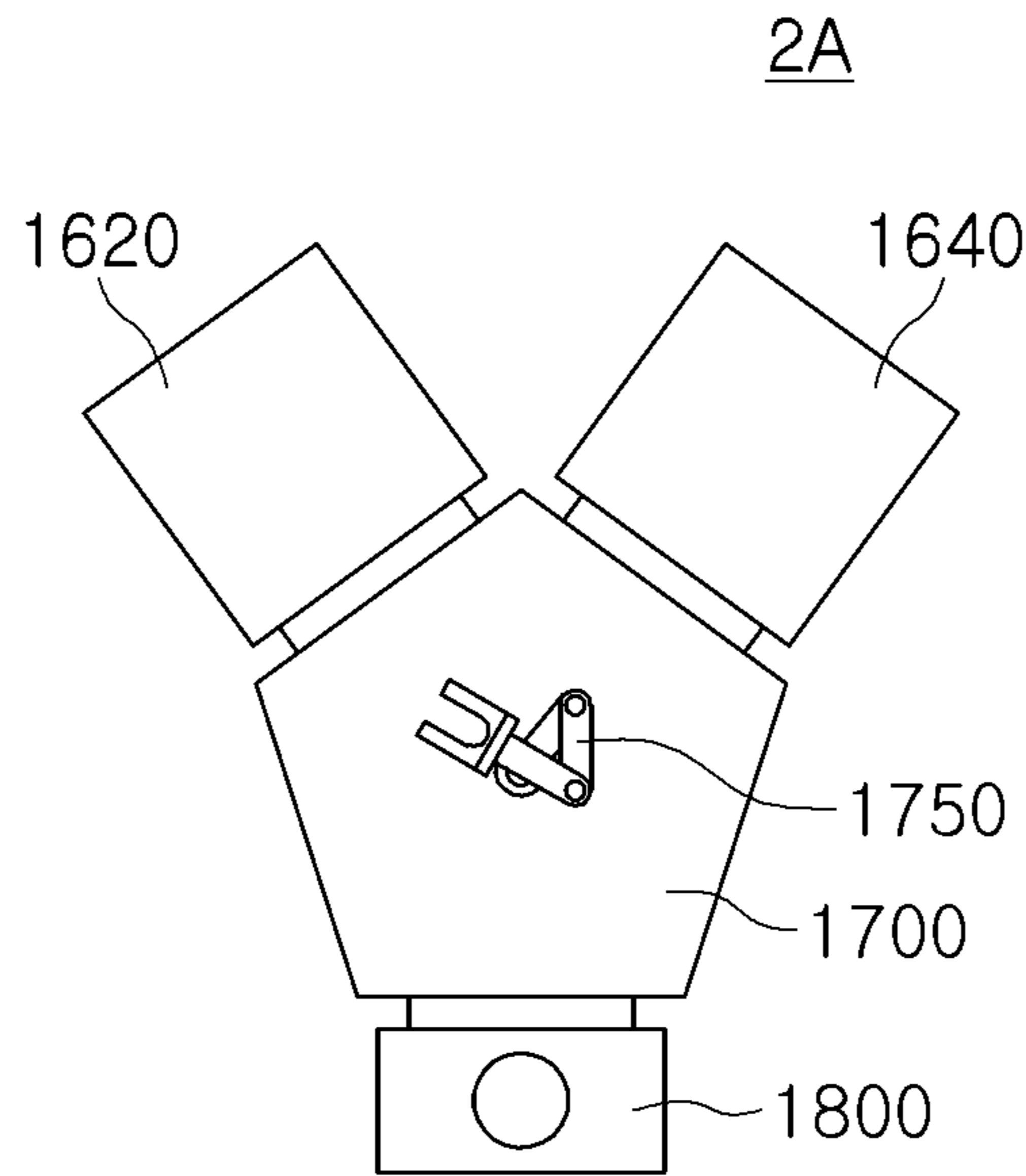


FIG. 14A

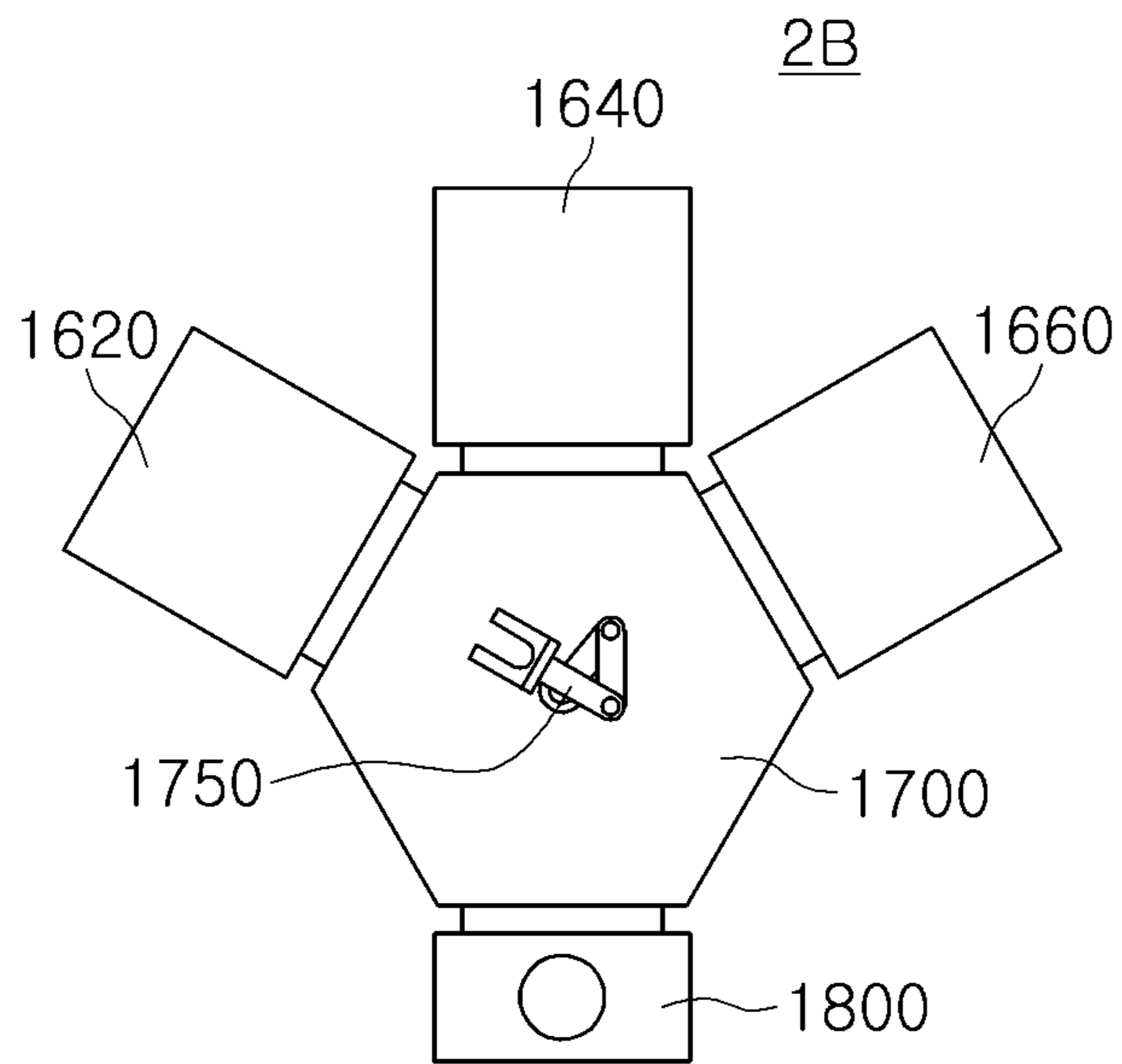


FIG. 14B

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**SEMICONDUCTOR DEVICE AND
APPARATUS OF MANUFACTURING THE
SAME**

CROSS-REFERENCE TO RELATED
APPLICATION(S)

This application is a continuation application of U.S. application Ser. No. 16/700,801, filed on Dec. 2, 2019, which claims priority under 35 U.S.C. § 119 to Korean Patent Application Nos. 10-2019-0032477 filed on Mar. 21, 2019 and 10-2019-0085709 filed on Jul. 16, 2019 in the Korean Intellectual Property Office, the disclosures of each of which are incorporated by reference herein in their entirety.

BACKGROUND

The present inventive concept relates to a semiconductor device and an apparatus for manufacturing the same.

Semiconductor devices have been decreased in size and designed to store high-capacity data. Accordingly, it has been necessary to increase integration density of transistors included in the semiconductor devices. For higher integration density of the semiconductor devices, a vertical transistor structure, instead of a planar transistor structure, has been developed.

SUMMARY

Example embodiments provide a semiconductor device having increased reliability and an apparatus for manufacturing the semiconductor device.

According to an exemplary embodiment of the present inventive concept, a semiconductor device includes a plurality of gate electrodes and a plurality of interlayer insulating layers that are alternately stacked on a substrate, a plurality of channel structures spaced apart from each other in a first direction and extending vertically through the plurality of gate electrodes and the plurality of interlayer insulating layers to the substrate, and a first separation region extending vertically through the plurality of gate electrodes and the plurality of interlayer insulating layers. Each gate electrode includes a first conductive layer and a second conductive layer, the first conductive layer disposed between the second conductive layer and each of two adjacent interlayer insulating layers. In a first region, between an outermost channel structure and the first separation region, of each gate electrode, the first conductive layer has a decreasing thickness toward the first separation region and the second conductive layer has an increasing thickness toward the first separation region.

According to an exemplary embodiment of the present inventive concept, a semiconductor device includes a plurality of gate electrodes stacked vertically to be spaced apart from each other on a substrate, a plurality of channel structures extending vertically through the plurality of gate electrodes to the substrate, and a separation region extending through the plurality of gate electrodes. Each gate electrode includes a first conductive layer with a laterally recessed region adjacent to an outermost channel structure, and a second conductive layer disposed in the laterally recessed region. The laterally recessed region has a decreasing width toward the outermost channel structure.

According to an exemplary embodiment of the present inventive concept, an apparatus of manufacturing a semiconductor device includes a gas supply unit including a first

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deposition gas source, a second deposition gas source and an etching gas source, a process chamber connected to the gas supply unit, a gas injection unit disposed in the process chamber and including a gas supply passage connected to the first deposition gas source, the second deposition gas source and the etching gas source, and a control unit configured to control the gas supply unit such that a first deposition process in which a first process gas of the first deposition gas source and a second process gas of the second deposition gas source are alternately supplied to the process chamber via the gas injection unit, an etching process in which a third process gas of the etching gas source is supplied to the process chamber via the gas injection unit, and a second deposition process in which the first process gas of the first deposition gas source and the second process gas of the second deposition gas source are alternately supplied to the process chamber from via the gas injection unit are sequentially performed.

BRIEF DESCRIPTION OF DRAWINGS

The above and other aspects, features, and advantages of the present inventive concept will be more clearly understood from the following detailed description, taken in conjunction with the accompanying drawings, in which:

FIG. 1 is a schematic block diagram of a semiconductor device according to example embodiments;

FIG. 2 is an equivalent circuit diagram of a cell array of a semiconductor device according to example embodiments;

FIG. 3 is a schematic plan view of a semiconductor device according to example embodiments;

FIG. 4 is a schematic cross-sectional view of a semiconductor device according to example embodiments;

FIGS. 5A to 5C are partially enlarged cross-sectional views of regions A, B and C of FIG. 4 according to example embodiments;

FIGS. 6A and 6B are partially enlarged cross-sectional views of a semiconductor device according to example embodiments;

FIGS. 7 and 8 are partially enlarged cross-sectional views of a semiconductor devices according to example embodiments;

FIG. 9 is a schematic cross-sectional view of a semiconductor device according to example embodiments;

FIG. 10 is a flowchart illustrating a method of manufacturing a semiconductor device according to example embodiments;

FIGS. 11A to 11I are cross-sectional views showing steps in a method of manufacturing a semiconductor device according to example embodiments;

FIG. 12 is a process flow diagram illustrating a method of manufacturing a semiconductor device according to example embodiments;

FIG. 13 is a schematic diagram of a manufacturing apparatus used to manufacture a semiconductor device according to example embodiments; and

FIGS. 14A and 14B are schematic diagrams of a manufacturing apparatus used to manufacture a semiconductor device according to example embodiments.

DETAILED DESCRIPTION

Hereinafter, the present inventive concept will be described with reference to the accompanying drawings.

FIG. 1 is a schematic block diagram of a semiconductor device according to example embodiments.

Referring to FIG. 1, a semiconductor device 10 may include a memory cell array 20 and a peripheral circuit 30. The peripheral circuit 30 may include a row decoder 32, a page buffer 34, an input and output buffer 35, a control logic 36, and a voltage generator 37.

The memory cell array 20 may include a plurality of memory blocks, and each of the memory blocks may include a plurality of memory cells. The plurality of memory cells may be connected to the row decoder 32 through a string select line SSL, wordlines WL, and a ground select line GSL, and may be connected to the page buffer 34 through bitlines BL. In example embodiments, a plurality of memory cells arranged in the same row may be connected to the same wordline WL, and a plurality of memory cells arranged in the same column may be connected to the same bitline BL.

The row decoder 32 may decode an input address ADDR and may generate and transfer driving signals of the wordline WL. The row decoder 32 may provide a wordline voltage generated from the voltage generator 37 to a selected wordline WL and unselected wordlines WL in response to control of the control logic 36.

The page buffer 34 may be connected to the memory cell array 20 through the bitlines BL, and may read information stored in the memory cells. The page buffer 34 may temporarily store data to be stored in the memory cells or may sense data stored in the memory cells in accordance with an operational mode. The page buffer 34 may include a column decoder and a sense amplifier. The column decoder may selectively activate the bitlines BL of the memory cell array 20, and the sense amplifier may sense a voltage of a bitline BL selected by the column decoder and may read data stored in a selected memory cell during a reading operation.

The input and output buffer 35 may receive data DATA and may transfer the data to the page buffer 34 when a program operation, which may be referred to as a writing operation, is performed and, in a reading operation, the input and output buffer 35 may output the data DATA received from the page buffer 34 to an external entity. The input and output buffer 35 may transfer an input address or an input command to the control logic 36.

The control logic 36 may control operations of the row decoder 32 and the page buffer 34. The control logic 36 may receive a control signal and an external voltage transferred from an external entity, and may operate depending on the received control signal. The control logic 36 may control a reading operation, a writing operation, and/or an erasing operation in response to the control signals.

The voltage generator 37 may generate voltages required for internal operations, such as a program voltage, a reading operation voltage, an erasing operation voltage, and the like, for example, using an external voltage. The voltages, generated by the voltage generator 37, may be transferred to the memory cell array 20 through the row decoder 32.

FIG. 2 is an equivalent circuit diagram of a cell array of a semiconductor device according to example embodiments.

Referring to FIG. 2, a memory cell array 20 may include a plurality of memory cell strings S including memory cells MC connected to each other in series, a ground select transistor GST connected in series to both ends of the memory cells MC, and string select transistors SST1 and SST2. The plurality of memory cell strings S may be connected to bitlines BL0 to BL2 in parallel. The plurality of memory cell strings S may be commonly connected to a common source line CSL. For example, the plurality of memory cell strings S may be arranged between the bitlines BL0 to BL2 and a single common source line CSL. In an

example embodiment, a plurality of common source lines CSL may be arranged two-dimensionally.

The memory cells MC, connected to each other in series, may be controlled by wordlines WL0 to WLn for selecting the memory cells MC. Each of the memory cells MC may include a data storage element. Gate electrodes of the memory cells MC, arranged at substantially the same distance from the common source line CSL, may be commonly connected to one of the wordlines WL0 to WLn to be in an equipotential state. Alternatively, even when the gate electrodes of the memory cells MC are arranged at substantially the same distance from the common source lines CSL, the gate electrodes arranged in different rows or columns may be independently controlled.

The ground select transistor GST may be controlled by the ground selection line GSL, and may be connected to the common source line CSL. The string select transistors SST1 and SST2 may be controlled by string selection lines SSL1 and SSL2, and may be connected to the bitlines BL0 to BL2.

In FIG. 2, one ground select transistor GST and two string select transistors SST1 and SST2 are illustrated as being connected to the plurality of memory cells MC connected in series. However, one of the transistors SST1 and SST2 may be respectively connected thereto, or a plurality of the ground select transistors GST may be respectively connected thereto. One or more dummy lines DWL, or a buffer line, may be further disposed between an uppermost wordline WLn among the wordlines WL0 to WLn and the string selection lines SSL1 and SSL2. In an example embodiment, the one or more dummy lines DWL may be disposed between a lowermost wordline WL0 and the ground selection line GSL.

When a signal is applied to the string select transistors SST1 and SST2 via the string selection lines SSL1 and SSL2, a signal applied through the bitlines BL0 to BL2 may be transferred to the memory cells MC, connected to each other in series, to perform a reading operation and a writing operation. In addition, an erasing operation may be performed to erase data, recorded in the memory cells MC, by applying a predetermined erasing voltage through the substrate. In an example embodiment, the memory cell array 20 may include at least one of the dummy memory cell strings electrically separated from the bitlines BL0 to BL2.

FIG. 3 is a schematic plan view of a semiconductor device according to example embodiments.

FIG. 4 shows a cross-sectional view of the semiconductor device taken along line I-I' of FIG. 3. For ease of description, only main components of the semiconductor device are illustrated in FIGS. 3 and 4.

FIGS. 5A to 5C are partially enlarged views of regions A, B, and C of FIG. 4, respectively.

Referring to FIGS. 3 and 4, a semiconductor device 100 may include a substrate 101, channel structures CH, extending in a direction perpendicular to an upper surface of the substrate 101, in which a channel layer 140 is disposed, a plurality of interlayer insulating layers 120 stacked along an external sidewalls of the channel structures CH, a plurality of gate electrodes 130, stacked alternately with the interlayer insulating layers 120, including a first conductive layer 130A and a second conductive layer 130B, and separation regions SR extending through a stacked structure of the interlayer insulating layers 120 and the gate electrodes 130 alternately stacked on the substrate 101. The semiconductor device 100 may further include a gate dielectric layer 145 disposed between the channel layer 140 and the gate electrodes 130, an epitaxial layer 107 disposed below the channel layer 140, channel pads 155 on an upper end of the

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channel structures CH, and a source conductive layer **180** and a source insulating layer **185** disposed in each of the separation regions SR.

In the semiconductor device **100**, a single memory cell string may be configured around each of the channel layer **140**, and the plurality of memory cell strings may be arranged in rows and columns in an x direction and a y direction different from the x direction.

The substrate **101** may have an upper surface extending in the x direction and the y direction. The substrate **101** may include a semiconductor material, for example, a group IV semiconductor, a group III-V compound semiconductor, or a group II-VI compound semiconductor. For example, the group IV semiconductor may include silicon, germanium, or silicon-germanium. The substrate **101** may be provided as a bulk wafer, an epitaxial layer, an epitaxial layer, a silicon on insulator (SOI) layer, a semiconductor on insulator (SeOI) layer, or the like.

The channel structures CH may be disposed on the substrate **101** to be spaced apart from each other in rows and columns. The channel structures CH may be arranged in the form of a lattice, or may be arranged zigzag in one direction. The channel structures CH may have side surfaces perpendicular to the substrate **101**, or may have sloped side surfaces narrowed in a direction toward the substrate **101** depending on an aspect ratio. Each of the channel structures CH may include the channel layer **140**, the gate dielectric layer **145**, the channel pad **155**, and the epitaxial layer **107**. Each of the channel structures CH may further include a channel insulating layer **150**.

In the channel structures CH, the channel layer **140** may be disposed in an annular shape to surround the channel insulating layer **150** therein. In some embodiments, the channel layer **140** may have a pillar shape such as a cylindrical shape or a prismatic shape without the channel insulating layer **150**. The channel layer **140** may be connected to the epitaxial layer **107**. The channel layer **140** may include a semiconductor material such as polycrystalline silicon or single-crystalline silicon, and the semiconductor material may be an undoped material or a material including p-type or n-type impurities. The channel structures CH, disposed on a straight line in the x direction, may be connected to different bitlines by arrangement of an upper interconnection structure connected to the channel pad **155**. A portion of the channel structures CH may be dummy channels which are not connected to the bitlines.

The gate dielectric layer **145** may be disposed between the gate electrodes **130** and the channel layer **140**. The gate dielectric layer **145** may include a tunneling layer **142**, a charge storage layer **143**, and a blocking layer **144** stacked sequentially from the channel layer **140**. The channel layer **140**, the tunneling layer **142** and the charge storage layer **143** may extend in a z direction perpendicular to the substrate **101**. The blocking layer **144** may be disposed to surround at least a portion of the gate electrode **130**. In this case, the blocking layer **144** may extend between the first conductive layer **130A** and each of two adjacent interlayer insulating layers **120**. In some embodiments, the channel layer **140** and the tunneling layer **142** may extend in a z direction and the charge storage layer **143** may also be disposed to surround the gate electrode **130** together with the blocking layer **144**. In this case, the charge storage layer **143** and the blocking layer **144** may extend the first conductive layer **130A** and each of two adjacent interlayer insulating layers **120**. Relative thicknesses of layers, constituting the gate dielectric layer **145**, are not limited to those illustrated in the drawings and may vary depending on example embodiments. In FIG.

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5A, a side surface of the blocking layer **144** is illustrated as being coplanar with a side surface of the gate electrode **130**. However, a shape of the blocking layer **144** is not limited thereto and may further extend toward, for example, side surfaces of the interlayer insulating layers **120** along the interlayer insulating layers **120**.

Electrons of the channel layer **140** may tunnel through the tunneling layer **142** to be stored in the charge storage layer **143** by Fowler-Nordheim (FN) tunneling mechanism. The tunneling layer **142** may include, for example, a silicon oxide (SiO_2), a silicon nitride (Si_3N_4), a silicon oxynitride (SiON), or combinations thereof. The charge storage layer **143** may be a charge trap layer, and may be formed of a silicon nitride. The blocking layer **144** may include a silicon oxide (SiO_2), a silicon nitride (Si_3N_4), a silicon oxynitride (SiON), a high-k dielectric, or combinations thereof. The term "high-k dielectric" refers to a dielectric material having a higher dielectric constant than a silicon oxide (SiO_2). The high-k dielectric may include, for example, an aluminum oxide (Al_2O_3), a tantalum oxide (Ta_2O_3), a titanium oxide (TiO_2), an yttrium oxide (Y_2O_3), a zirconium oxide (ZrO_2), a zirconium silicon oxide (ZrSi_xO_y), a hafnium oxide (HfO_2), a hafnium silicon oxide (HfSi_xO_y), a lanthanum oxide (La_2O_3), a lanthanum aluminum oxide (LaAl_xO_y), a lanthanum hafnium oxide (LaHf_xO_y), a hafnium aluminum oxide (HfAl_xO_y), a praseodymium oxide (Pr_2O_3), or combinations thereof.

The epitaxial layer **107** may be disposed on the substrate **101** in the lower portion of the channel structures CH, and may be disposed on a side surface of the at least one gate electrode **130**. The epitaxial layer **107** may be disposed in a recessed region of the substrate **101**. An upper surface of the epitaxial layer **107** may have a height greater than a height of an upper surface of the lowermost gate electrode **130** and less than a height of a lower surface of the upper gate electrode **130** adjacent to the lowermost gate electrode **130**, but the height of the upper surface of the epitaxial layer **107** is not limited thereto. Even when an aspect ratio of the channel structure CH is increased, the channel layer **140** may be stably electrically connected to the substrate **101** by the epitaxial layer **107** and characteristics of the ground select transistor GST between memory cell strings may be uniform. In some embodiments, the epitaxial layer **107** may be omitted. In this case, the channel layer **140** may be directly connected to the substrate **101**.

The channel pad **155** may be disposed above the channel layer **140** in the channel structures CH. The channel pad **155** may be disposed to cover an upper surface of the channel insulating layer **150** and to be electrically connected to the channel layer **140**. The channel pads **155** may include, for example, doped polysilicon.

The gate electrodes **130** may be disposed to be spaced apart from each other in a direction perpendicular to the substrate **101** along a side surface of each of the channel structures CH. The gate electrodes **130** may include a ground select electrode **130G**, a cell electrode **130M**, and a string select electrode **130S**, which constitute gate electrodes of a ground select transistor, a plurality of memory cells, and a string select transistor, respectively. The gate electrodes **130** may extend while forming a ground select line, wordlines, and a string select line. The wordlines may be commonly connected in adjacent memory cell strings of a predetermined unit arranged in the x and y directions. The string select electrode **130S**, constituting the string select line, may be separated from each other at regular intervals in the x direction by an upper insulating layer **103**. However, the number of the string selection electrodes **130S**, separated

by the upper insulating layer **103**, is not limited to the number illustrated in the drawings.

In some embodiments, one or more string select electrodes **130S** and one or more ground select electrodes **130G** may be provided, and may have the same or different structures as the cell electrodes **130M**. Some gate electrodes **130**, for example, gate electrodes **130**, adjacent to the string select electrodes **130S** or the ground select electrodes **130G**, may be dummy gate electrodes.

Referring to FIGS. **5A** to **5C**, each of the gate electrodes **130** may include a first conductive layer **130A**, adjacent to the interlayer insulating layers **120** and the channel structure **CH**, and a second conductive layer **130B** on the first conductive layer **130A**.

The first conductive layer **130A** may be disposed on upper and lower surfaces of the interlayer insulating layers **120** and may be disposed on sidewalls of the channel structure **CH**. Accordingly, the first conductive layer **130A** may be disposed to have a laterally recessed region **LR** toward the channel structure **CH**. The first conductive layer **130A** may be interposed between a portion of the gate dielectric layer **145** and the second conductive layer **130B**. For example, the first conductive layer **130A** may be interposed between the blocking layer **144** of the gate dielectric layer **145** and the second conductive layer **130B**. In this case, the blocking layer **144** may be disposed between the channel layer **140** and the first conductive layer **130** and between each of two adjacent interlayer insulating layers **120** and the first conductive layer **130**.

The first conductive layer **130A** may decrease in thickness on the upper and lower surfaces of the interlayer insulating layers **120** from an outermost channel structure **CH** adjacent to the separation region **SR** in the *x* direction to the separation region **SR**. For example, when a region of the gate electrode **130** adjacent to the separation region **SR** is referred to as an edge region **GE**, the first conductive layer **130A** may decrease in thickness in a direction toward the separation region **SR** in at least the edge region **GE**, as illustrated in FIG. **5A**. Accordingly, the laterally recessed region **LR** may have a larger width in a *z* direction in a region adjacent to the separation region **SR** than in a region adjacent to the channel structure **CH**. In an example embodiment, the laterally recessed region **LR** may have a decreasing width toward the channel structure **CH** in the *x* direction. In particular, the edge region **GE** may include a region between channel structures **CH** adjacent to the separation region **SR** in the *x* direction and the separation region **SR**.

The second conductive layer **130B** may be disposed to fill an internal side (i.e., the laterally recessed region **LR**) of the first conductive layer **130A** between two interlayer insulating layers **120** that are vertically adjacent to each other. According to a shape of the first conductive layer **130A**, the second conductive layer **130B** may have a first thickness **T1** in a region, distant from the separation region **SR**, and a second thickness **T2**, greater than the first thickness **T1**, in a region adjacent to the separation region **SR** and may have an increasing thickness toward the separation region **SR**. The upper surface of the second conductive layer **130B** may have an increasing height toward the separation region **SR**. The thickness increase of the second conductive layer **130B** may be continuous. However, the present inventive concept is not limited thereto. In some embodiments, the second conductive layer **130B** may have a shape in which the height is increased stepwise in a staircase form or increased gradually and stepwise in a direction toward the separation region **SR**.

For example, the first conductive layer **130A** may have a thickness ranging from about 0.1 nm to about 3 nm and the

second conductive layer **130B** may have a thickness ranging from about 10 nm to about 30 nm on an internal side of the first conductive layer **130A**. In an example embodiment, the first conductive layer **130A** and the second conductive layer **130B** may be substantially symmetrical between two adjacent separation regions **SR** in the *x* direction. For example, an uppermost gate electrode **130** (e.g., the string select electrode **130S**) may be symmetrical with respect to the upper insulating layer **103**, and a gate electrode **130** below the uppermost gate electrode **130** (e.g., the cell electrode **130M**) may be symmetrical with respect to an extending region of the upper insulating layer **103** in the *z* direction. In an exemplary embodiment, the upper insulating layer **103** and its extending region in the *z* direction may be positioned in a center region between the two adjacent separation regions **SR**. In this case, the gate electrode **130** including the first conductive layer **130A** and the second conductive layer **130B** may be symmetrical with respect to the center region of the two adjacent separation regions **SR**.

The first conductive layer **130A** and the second conductive layer **130B** may include the same material or different materials. The first conductive layer **130A** and the second conductive layer **130B** may include a metal material such as tungsten (**W**), cobalt (**Co**), molybdenum (**Mo**), ruthenium (**Ru**), nickel (**Ni**), or the like. In some embodiments, the first conductive layer **130A** and the second conductive layer **130B** may include polycrystalline silicon or a metal silicide material. In some embodiments, the gate electrodes **130** may further include a diffusion barrier layer to protect the channel structures **CH** in the process of forming the gate electrodes **130**. In this case, the diffusion barrier layer may be disposed between the first conductive layer **130A** and each of the channel structures **CH** and between the first conductive layer **130A** and each of the two adjacent interlayer insulating layers **120**.

The first conductive layer **130A** and the second conductive layer **130B** may have an interface **IF** therebetween that may be identified by, for example, a transmission electron microscopy (**TEM**). For example, even when the materials of the first conductive layer **130A** and the second conductive layer **130B** are identical to each other, the interface **IF** may be recognized due to discontinuity of a crystal structure, as, for example, grain boundaries. In an example embodiment, the grain boundaries between the first conductive layer **130A** and the second conductive layer **130B** may be continuous or discontinuous. An interface **IF** between the first conductive layer **130A** and the second conductive layer **130B** may form a sloped surface. For example, the interface **IF** between the first conductive layer **130A** and the second conductive layer **130B** may be sloped with respect to the *x*-direction in the edge region **GE**. The first conductive layer **130A** and the second conductive layer **130B** are illustrated as being recessed toward the channel layer **140** by a predetermined distance from a side surface of the interlayer insulating layer **120** in contact with the separation region **SR**, a shape of the first conductive layer **130A** and the second conductive layer **130B** is not limited thereto. For example, the first conductive layer **130A** and the second conductive layer **130B** may have sidewalls, adjacent to the separation region **SR**, coplanar with the interlayer insulating layers **120**.

As illustrated in FIG. **5B**, the first conductive layer **130A** and the second conductive layer **130B** have a substantially uniform thickness in a first region spaced farthest apart from the separation regions **SR**. Accordingly, the interface **IF** may also be a substantially planar surface. For example, the interface **IF** may be substantially parallel to the *x* direction. The second conductive layer **130B** may have a third thick-

ness T3, and the third thickness T3 may less than or equal to the first thickness T1. This is because the first conductive layer 130A has a thickness greater than or equal to a maximum thickness in the edge region GE.

As illustrated in FIG. 5C, in a second region between the first region and the edge region GE, the first conductive layer 130A and the second conductive layer 130B have a substantially uniform thickness, or may have thicknesses decreased and increased in a direction toward the edge region GE, respectively. Accordingly, the interface IF may also be substantially parallel to the x direction or sloped with respect to the x direction. The second conductive layer 130B may have a fourth thickness T4 and a fifth thickness T5 on opposite ends adjacent to the channel structures CH. In some embodiments, the fourth thickness T4 may be substantially the same as the fifth thickness T5 or less than the fifth thickness T5. The fourth thickness T4 may be greater than or equal to the third thickness T3, and the fifth thickness T5 may be less than or equal to the first thickness T1. This is because the thickness of the first conductive layer 130A in the second region may be higher than or equal to the maximum thickness in the edge region GE.

In example embodiments, the thickness of the first conductive layer 130A may be gradually decreased in the x direction from the first region to the edge region GE via the second region. Alternatively, the first conductive layer 130A may have substantially the same thickness as the maximum thickness of the edge region GE in the first region and the second region, and may have a thickness decreased only in the edge region GE.

The interlayer insulating layers 120 may be disposed between the gate electrodes 130. Similar to the gate electrodes 130, the interlayer insulating layers 120 may be disposed to be spaced apart from each other in the z direction perpendicular to the upper surface of the substrate 101 and may extend in the x direction. The interlayer insulating layers 120 may include an insulating material such as silicon oxide or silicon nitride. Side surfaces of the interlayer insulating layers 120 may have a structure protruding from the side surfaces of the gate electrodes 130 to the separation region SR. However, in example embodiments, side surfaces of the interlayer insulating layers 120 may be coplanar with side surfaces of the gate electrodes 130.

The separation regions SR may extend through the gate electrodes 130 and the interlayer insulating layers 120 between the channel structures CH in the z direction, and may be connected to the substrate 101. The source conductive layer 180 and the source insulating layer 185 may be disposed in the separation regions SR. The source conductive layer 180 may have a shape in which a width is decreased in a direction toward the substrate 101 due to a high aspect ratio, but a shape of the source conductive layer 180 is not limited thereto. The source conductive layer 180 may have a side surface perpendicular to the upper surface of the substrate 101.

The source conductive layer 180 may be electrically insulated from the gate electrodes 130 by the source insulating layer 185. Accordingly, stacked structures of the gate electrodes 130 may be separated from each other in the x direction by the source conductive layer 180 interposed therebetween. The source conductive layer 180 may be disposed in the form of a line extending in the y direction and may correspond to a common source line of the semiconductor device 100. The source conductive layer 180 may be repeatedly arranged at a predetermined interval in the x direction, for example, every four columns to eight columns of the channel structures CH, but the arrangement of the

source conductive layer 180 is not limited thereto. The source insulating layer 185 may partially extend and protrude between the interlayer insulating layers 120 to be in contact with side surfaces of the gate electrodes 130. For example, the source insulating layer 185 may include a plurality of protrusions each of which is contact with a side surface of a corresponding one of the gate electrodes 130 and is disposed between two adjacent interlayer insulating layers 120. The source conductive layer 180 may include a conductive material such as polycrystalline silicon, metal, or the like, and the source insulating layer 185 may include an insulating material such as silicon oxide, silicon nitride, or the like. In some embodiments, the separation regions SR may be filled with only an insulating material without the source conductive layer 180. In this case, a region corresponding to the common source line may be disposed in the substrate 101 or on the substrate 101.

The cell region insulating layer 190 may be disposed on the stacked structure of the gate electrodes 130 and may include an insulating material such as silicon oxide, silicon nitride, or the like.

FIGS. 6A and 6B are partially enlarged cross-sectional views of semiconductor devices according to example embodiments. FIGS. 6A and 6B illustrate enlarged versions of regions corresponding to the region A of FIG. 4.

Referring to FIG. 6A, in a semiconductor device 100a, a first conductive layer 130A and a second conductive layer 130B may include first and second nucleation layers 130As and 130Bs and first and second bulk layers 130Ab and 130Bb, respectively.

The first and second nucleation layers 130As and 130Bs may be formed first to provide a nucleation site to assist nucleation for growth of subsequent first and second bulk layers 130Ab and 130Bb. The first and second bulk layers 130Ab and 130Bb may be respectively grown based on the first and second nucleation layers 130As and 130Bs to have desired thicknesses.

The first and second nucleation layers 130As and 130Bs and the first and second bulk layers 130Ab and 130Bb may be formed under different process conditions and may have different thicknesses. In example embodiments, the first and second nucleation layers 130As and 130Bs have an amorphous structure, while the first and second bulk layers 130Ab and 130Bb have a crystalline structure. For example, the first and second nucleation layers 130As and 130Bs and the first and second bulk layers 130Ab and 130Bb may be formed using different reactant gases, and may be formed at different deposition rates. Each of the first and second nucleation layers 130As and 130Bs may have a thickness of about 3 nm or less, for example, a thickness ranging from about 10 angstroms to about 20 angstroms, and may have a substantially uniform thickness. The first bulk layer 130Ab may have a thickness decreased on one surface of the interlayer insulating layer 120 in a direction toward the separation region SR, and the second bulk layer 130Bb have a thickness increased in a direction toward the separation region SR. In some embodiments, the first and second nucleation layers 130As and 130Bs and the first and second bulk layers 130Ab and 130Bb may include different impurities.

For example, when the gate electrode 130 is formed of tungsten (W) and WF_6 is used as a source gas, the first and second nucleation layers 130As and 130Bs may serve to prevent diffusion of residual fluorine (F). Accordingly, the first and second nucleation layers 130As and 130Bs may prevent fluorine (F) in the gate electrode 130 from being

diffused to the gate dielectric layer **145**, thereby preventing deterioration in electrical characteristics of the semiconductor device **100a**.

Referring to FIG. **6B**, in a semiconductor device **100b**, a first conductive layer **130A** may include a first nucleation layer **130As** and a first bulk layer **130Ab**, and a second conductive layer **130B** may substantially include only the same layer as a bulk layer without a nucleation layer.

In the present embodiment, the second conductive layer **130B** is provided on the first conductive layer **130A** without forming a nucleation layer thereon. In this case, process efficiency may be increased as compared with the example embodiment of FIG. **6A**.

FIGS. **7** and **8** are partially enlarged cross-sectional views of the region A of FIG. **4**.

Referring to FIG. **7**, in a semiconductor device **100c**, a first conductive layer **130A** may extend to a separation region SR to be shorter than a blocking layer **144** of a gate dielectric layer **145**. Accordingly, the first conductive layer **130A** may not be disposed in at least one region on the blocking layer **144**, and a second conductive layer **130B** may be in contact with the blocking layer **144**. The term “contact,” as used herein, refers to a direct connection (i.e., touching) unless the context indicates otherwise. More specifically, the second conductive layer **130B** may fill a space between the blocking layer **144** on upper and lower interlayer insulating layers **120** in a region adjacent to the separation region SR. In example embodiments, a length of the region, in which the first conductive layer **130A** is not disposed on the blocking layer **144**, may be variously changed.

Referring to FIG. **8**, in a semiconductor device **100d**, a blocking layer **144a** of a gate dielectric layer **145a** may be disposed to extend in a direction perpendicular to an upper surface of a substrate **101**, similar to a channel structure CH, rather than in a horizontal direction along a gate electrode **130**. Accordingly, a first conductive layer **130A** of a gate electrode **130** may be in contact with interlayer insulating layers **120**.

FIG. **9** is a schematic cross-sectional view of a semiconductor device according to example embodiments.

Referring to FIG. **9**, a semiconductor device **200** may include a memory cell region CELL and a peripheral circuit region PERI, which are vertically stacked. The memory cell region CELL may be disposed on an upper surface of the peripheral circuit region PERI. For example, the semiconductor device **100** of FIG. **4** includes the peripheral circuit region PERI disposed on the substrate **101** in a region, not illustrated, while the semiconductor device **200** according to the present embodiment may include the memory cell region CELL and the peripheral circuit region PERI stacked vertically. In example embodiments, the cell region CELL may be disposed below the peripheral circuit region PERI. The descriptions, made with reference to FIGS. **3** and **4**, may be identically applied to the description of the memory cell region CELL.

The peripheral circuit region PERI may include a base substrate **201**, circuit elements **220** disposed on the base substrate **201**, circuit contact plugs **270**, and circuit interconnection lines **280**.

The base substrate **201** may have an upper surface extending in an x direction and a y direction. In the base substrate **201**, isolation layers may be formed to define an active region. Source/drain regions **205**, including impurities, may be disposed in a portion of the active region. The base substrate **201** may include a semiconductor material, for

example, a group IV semiconductor, a group III-V compound semiconductor, or a group II-VI compound semiconductor.

The circuit elements **220** may include planar transistors. Each of the circuit elements **220** may include a circuit gate dielectric layer **222**, a spacer layer **224**, and a circuit gate electrode **225**. Source/drain regions **205** may be disposed in the base substrate **201** on opposite sides adjacent to the circuit gate electrode **225**.

A peripheral region insulating layer **290** may be disposed on the circuit element **220** on the base substrate **201**. Circuit contact plugs **270** may be connected to the source/drain regions **205** through the peripheral region insulating layer **290**. Electrical signals may be applied to the circuit element **220** by the circuit contact plugs **270**. In a region, not illustrated, the circuit contact plugs **270** may also be connected to the circuit gate electrode **225**. The circuit interconnection lines **280** may be connected to the circuit contact plugs **270** and may be disposed as a plurality of layers.

In the semiconductor device **200**, after the peripheral circuit region PERI is formed, a substrate **101** in the memory cell region CELL may be formed on the peripheral circuit region PERI to form the memory cell region CELL. The substrate **101** may be formed to have the same size as the base substrate **201** or to have a smaller size than the base substrate **201**. The memory cell area CELL and the peripheral circuit area PERI may be connected to each other in a region, not illustrated. For example, one end of the gate electrode **130** in the y direction may be electrically connected to the circuit elements **220**.

FIG. **10** is a flowchart illustrating a method of manufacturing a semiconductor device according to example embodiments.

FIGS. **11A** to **11I** are cross-sectional views showing the steps in a method of manufacturing the semiconductor device of FIG. **4** according to example embodiments.

Referring to FIGS. **10** and **11A**, sacrificial layers **110** and interlayer insulating layers **120** may be alternately stacked on the substrate **101** to form a stacked structure (S**110**).

The sacrificial layers **110** may be replaced with gate electrodes **130** in a subsequent process. The sacrificial layers **110** may be formed of a material different from a material of the interlayer insulating layers **120**. For example, the interlayer insulating layer **120** may be formed of at least one of a silicon oxide and a silicon nitride, and the sacrificial layers **110** may be formed of a material, different from the material of the interlayer insulating layer **120**, selected from silicon, a silicon oxide, a silicon carbide, and a silicon nitride. In example embodiments, thicknesses of the interlayer insulating layers **120** may not all be equal to each other. For example, a lowermost interlayer insulating layer **120** may be formed to have a relatively large thickness, and an uppermost interlayer insulating layer **120** may be formed to have a relatively small thickness. The thicknesses of the interlayer insulating layers **120** and the sacrificial layers **110** and the number of layers, constituting the same, may be variously changed from those illustrated in the drawings. A cell region insulating layer **190** may be formed on an uppermost portion.

Referring to FIGS. **10** and **11B**, an upper insulating layer **103** may be formed, and channel structures CH may be formed to penetrate through the stacked structure (S**120**).

The upper insulating layer **103** may be formed by removing a predetermined number of sacrificial layers **110** and interlayer insulating layers **120** from an uppermost portion of the stacked structure using an additional mask layer. The upper insulating layer **103** may be formed by depositing an

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insulating material on a region in which the sacrificial layers **110** and the interlayer insulating layers **120** are removed. The upper insulating layer **103** and the interlayer insulating layer **120** may be formed of a material having etching selectivity with respect to the sacrificial layers **110**. In an example embodiment, the upper insulating layer **103** may be formed of the same material as the interlayer insulating layer **120**.

Next, for formation of channel structure CH, channel holes may be formed. The channel holes may be formed by anisotropically etching the stacked structure, and may be formed in a hole shape, for example. Due to a height of the stacked structure, sidewalls of the channel holes may not be perpendicular to an upper surface of the substrate **101**. The channel holes may be formed in a portion of the substrate **101**. For example, the portion of the substrate **101**, in forming the channel holes, may be recessed from the upper surface of the substrate **101**.

Next, an epitaxial layer **107**, a gate dielectric layer **145**, a channel layer **140**, a channel insulating layer **150**, and a channel pad **155** may be formed in the channel holes to form a channel structure CH. The epitaxial layer **107** may be formed using a selective epitaxial growth (SEG) process. The epitaxial layer **107** may be formed as a single layer or a plurality of layers, and may include doped or undoped polycrystalline silicon, single-crystalline silicon, polycrystalline germanium, or single-crystalline germanium.

The gate dielectric layer **145** may be formed to have a uniform thickness using atomic layer deposition (ALD) or chemical vapor deposition (CVD). In this process step, the entirety or a portion of the gate dielectric layer **145** may be formed and a portion, extending in a direction perpendicular to the substrate **101** along the channel structures CH, for example, the tunneling layer **142** and the charge storage layer **143** of FIG. 4 may be formed.

The channel layer **140** may be formed on the gate dielectric layer **145** in the channel holes. The channel insulating layer **150** may be formed to fill the channel holes and may be an insulating material. However, in some embodiments, the channel holes may be filled with a conductive material, rather than the channel insulating layer **150**. The channel pad **155** may be formed of a conductive material, for example, polycrystalline silicon.

Referring to FIGS. 10 and 11C, separation regions SR may be formed to separate and penetrate through the stacked structure at predetermined intervals (S130).

In example embodiments, before forming the separation regions SR, an additional layer may be formed on the cell region insulating layer **190** and the channel pad **155** to prevent damage to the channel pad **155**, the underlying channel layer **140**, and the like. In an example embodiment, the additional layer and the cell region insulating layer **190** may be formed of the same material. The separation regions SR may be formed by forming a mask layer using a photolithography process and anisotropically etching the stacked structure of the sacrificial layers **110** and the interlayer insulating layers **120**. The separation regions SR may be formed in a shape of trenches extending in the y direction. The source conductive layer **180** and the source insulating layer **185** of FIG. 4 may be disposed in each of the separation regions SR.

Referring to FIGS. 10 and 11D, lateral openings LT may be formed by removing the sacrificial layers **110** exposed through the separation regions SR (S140).

The sacrificial layers **110** may be selectively removed with respect to the interlayer insulating layers **120** using, for example, wet etching. Accordingly, the lateral openings LT

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may be formed between the interlayer insulating layers **120**, and sidewalls of the channel structures CH may be partially exposed through the lateral openings LT.

Referring to FIGS. 10 and 11E, a preliminary first conductive layer **130AP** of the gate electrode **130** may be formed in the lateral openings LT (S150).

Before forming the preliminary first conductive layer **130AP**, a portion of the gate dielectric layer **145**, for example, the blocking layer **144** of FIG. 4, may be formed in the lateral openings LT. In some embodiments, when the blocking layer **144** is formed on internal sidewalls of the channel structures CH, the blocking layer **144** may not be formed in this process step and may be formed in advance together with the channel layer **140**.

The preliminary first conductive layer **130AP** may be formed by, for example, a CVD process or an ALD process. The preliminary first conductive layer **130AP** may be formed to have a substantially uniform thickness along the upper and lower surfaces of the interlayer insulating layers **120** and the sidewalls of the channel structures CH, and may have a thickness insufficient to fill the lateral openings LT. Accordingly, the preliminary first conductive layer **130AP** may have a laterally recessed region LR formed concavely toward the channel structure CH.

When the preliminary first conductive layer **130AP** is formed of tungsten (W), at least one of WF_6 , WCl_6 , WCl_5 , $W(CO)_6$, $W(C_6H_6)_2$, $W(PF_3)_6$, $W(allyl)_4$, and (1, 5-COD) $W(CO)_4$, $(C_5H_5)_2WH_2$ may be used as a source gas and at least one of B_2H_6 , SiH_4 , and H_2 may be used as a reactant gas. Similar to the embodiments of FIGS. 6A and 6B, the preliminary first conductive layer **130AP** may include a nucleation layer and a bulk layer. In this case, a reactant gas, used to form the nucleation layer, may have a higher decomposition rate of the source gas than a reactant gas used to form the bulk layer.

Referring to FIGS. 10 and 11F, a portion of the preliminary first conductive layer **130AP** may be removed to have a thickness decreased in a direction toward the separation regions SR (S160).

The process of removing a portion of the preliminary first conductive layer **130AP** may be a dry etching process using plasma or a dry etching process using no plasma. The dry etching process using plasma may use, for example, at least one radical of NF_3 , Cl_2 , and F_2 . The dry etching process using no plasma may use a source gas used when the preliminary first conductive layer **130AP** is deposited. For example, when the preliminary first conductive layer **130AP** is formed of tungsten (W), etching may be performed using at least one source gas of WF_6 , WCl_6 , WCl_5 , $W(CO)_6$, $W(C_6H_6)_2$, $W(PF_3)_6$, $W(allyl)_4$, and (1, 5-COD) $W(CO)_4$, $(C_5H_5)_2WH_2$. For example, etching may be performed through a chemical reaction by introducing only a source gas without a reactant gas such that the source gas for use in deposition is used as an etching gas.

During the etching process, the preliminary first conductive layer **130AP**, adjacent to the separation region SR and relatively more exposed to an etchant, may be relatively more removed and the preliminary first conductive layer **130AP**, spaced apart from the separation region SR and relatively less exposed to the etchant, may be relatively less removed. Accordingly, the first conductive layer **130A** may have a thickness gradually increased in a direction from an external side adjacent to the separation region SR to the channel structures CH and may have a surface profile sloped on upper and lower surfaces of the interlayer insulating layers **120**. The first conductive layer **130A** may not be etched or rarely etched between the channel structures CH,

disposed not to be adjacent to the separation region SR, to have a substantially planar upper surface, but a shape of the upper surface of the first conductive layer 130A is not limited thereto. In some embodiments, the first conductive layer 130A may have, for example, a sloped upper surface even between internal channel structures CH disposed not to be adjacent to the separation region SR.

In this process step, etching conditions may be controlled such that the interlayer insulating layers 120 are not removed while removing a portion of the preliminary first conductive layer 130AP. In some embodiments, a portion of the interlayer insulating layers 120 adjacent to the separation region SR may be removed while removing a portion of the preliminary first conductive layer 130AP. In the case of the blocking layer 144, at least a portion of the blocking layer 144 may be removed on sidewalls of the interlayer insulating layers 120 together with the preliminary first conductive layer 130AP.

Referring to FIGS. 10 and 11G, a preliminary second conductive layer 130BP may be formed on the first conductive layer 130A to form gate electrodes 130 (S170).

The preliminary second conductive layer 130BP may be formed by, for example, a CVD or ALD process. The preliminary second conductive layer 130BP may be formed to completely fill the lateral openings LT between the interlayer insulating layers 120.

When the preliminary second conductive layer 130BP is formed of tungsten (W), at least one of WF_6 , WCl_6 , WCl_5 , $W(CO)_6$, $W(C_6H_6)_2$, $W(PF_3)_6$, $W(allyl)_4$, and (1, 5-COD) $W(CO)_4$, $(C_5H_5)_2WH_2$ may be used as a source gas, and deposition may be performed using at least one reactant gas of B_2H_6 , SiH_4 , and H_2 . In some embodiments, the preliminary second conductive layer 130BP may include a nucleation layer and a bulk layer, or may include only a bulk layer.

Since the laterally recessed regions LR have a profile, in which an opening width is increased in a direction toward the separation region SR, depending on a shape of the first conductive layer 130A, step coverage of the preliminary second conductive layer 130BP may be increased and gap-filling capability thereof may be increased. Accordingly, in the semiconductor device, a void-free gate electrode 130 may be formed even when the number of gate electrodes 130, stacked to increase integration density, is increased and a distance between adjacent separation regions SR is increased to prevent inclination of the stacked structure during a process of forming the semiconductor device.

Referring to FIG. 11H, a material of the gate electrode 130 formed on the sidewalls of the interlayer insulating layers 120 and on the substrate 101 in the separation regions SR, may be removed.

The preliminary second conductive layer 130BP, formed in the separation regions SR, may be removed by an etching process such that the gate electrode 130 is disposed only in the lateral openings LT. The etching process may be, for example, a wet etching process. In the etching process, the preliminary second conductive layer 130BP may be partially removed and recessed to form the second conductive layer 130B, and the first conductive layer 130A of FIG. 11G may be partially removed with the partial removal of the preliminary second conductive layer 130BP. The gate electrode 130 may include the first conductive layer 130A partially removed and the second conductive layer 130B. As a result, side surfaces of the gate electrodes 130 may be defined. For electrical isolation between gate electrodes 130 vertically adjacent to each other, the side surfaces of the gate electrodes 130 may be further recessed inwardly toward the channel structures CH than the side surfaces of the interlayer

insulating layers 120. In this process step, the blocking layer 144 formed in the separation regions SR may also be removed to form side surfaces of the blocking layer 144 at the same or similar positions as the side surfaces of the gate electrodes 130.

Referring to FIG. 11I, a source insulating layer 185 may be formed in the separation regions SR.

The source insulating layer 185 may be formed by forming an insulating material to cover the side surfaces of the gate electrodes 130 and the interlayer insulating layers 120 and removing the insulating material on the substrate 101 to expose the upper surface of the substrate 101.

Referring to FIG. 4, a conductive material may be deposited between source insulating layers 185 on opposite sides of the separation regions SR to form a source conductive layer 180. Then, interconnection structures such as contact plugs and bitlines may be further formed on the channel pads 155 to manufacture the semiconductor device 100.

FIG. 12 is a process flow diagram illustrating a method of manufacturing a semiconductor device according to example embodiments.

Referring to FIG. 12, an injection flow of process gases in the process step of forming the first conductive layer 130A and the second conductive layer 130B, described with reference to FIGS. 11E to 11G, is illustrated. A gate electrode 130 may be formed by sequentially performing a first deposition process to form a preliminary first conductive layer 130AP, an etching process to remove a portion of the preliminary first conductive layer 130AP, and a second deposition process to form the second conductive layer 130B.

In the first deposition process, a source gas and a reactant gas may be alternately supplied to form the preliminary first conductive layer 130AP. After each of the source gas and the reactant gas is supplied, a purge gas may be supplied. One deposition cycle may be repeatedly performed two or more times to form the preliminary first conductive layer 130AP.

The source gas may include a precursor containing a material forming the preliminary first conductive layer 130AP. The precursor may be supplied in a gaseous state or may be supplied with an inert gas as a carrier gas. The reactant gas may be supplied to assist nucleation of the precursor, and may be a gas for oxidizing or reducing the precursor. Argon (Ar), helium (He), or nitrogen (N_2) may be used as the purge gas. Remaining by-products and non-adsorbed source and reactant gases may be removed by the purge gas. For example, when the preliminary first conductive layer 130AP is formed of tungsten (W), the source gas may be one of WF_6 , WCl_6 , WCl_5 , $W(CO)_6$, $W(C_6H_6)_2$, $W(PF_3)_6$, $W(allyl)_4$, and (1, 5-COD) $W(CO)_4$, $(C_5H_5)_2WH_2$. The reactant gas may be at least one of B_2H_6 , SiH_4 , and H_2 .

In the etching process, an etching gas may be supplied to remove a portion of the preliminary first conductive layer 130AP. After the etching gas is supplied, the purge gas may be supplied. The etching gas may be supplied for a predetermined time $\Delta T2$, which may be longer than or equal to a supply time $\Delta T1$ of the source gas in the first deposition process.

The etching gas may include a precursor containing a material forming the preliminary first conductive layer 130AP. When the preliminary first conductive layer 130AP is formed of tungsten (W), the etching gas may include at least one of WF_6 , WCl_6 , WCl_5 , $W(CO)_6$, $W(C_6H_6)_2$, $W(PF_3)_6$, $W(allyl)_4$, (1, 5-COD) $W(CO)_4$, and $(C_5H_5)_2WH_2$. In an example embodiment, the source gas may be WF_6 , and the etching gas may be WCl_6 having relatively large etching characteristics. Alternatively, in an example embodiment,

the source gas and the etching gas may be the same gas. In the etching process, one cycle may also be repeatedly performed two or more times. In this embodiment, the preliminary first conductive layer **130AP** may be removed using a precursor, available as the source gas, without using plasma. Thus, a process may be simplified and may be performed using a single manufacturing apparatus.

In the second deposition process, a source gas and a reactant gas may be alternately supplied to form the second conductive layer **130B**. After each of the source gas and the reactant gas is supplied, a purge gas may be supplied. One deposition cycle may be repeatedly performed two or more times to form the second conductive layer **130B**. The description of the first deposition process may be identically applied to the above gases.

The first deposition process, the etching process, and the second deposition process may be performed in a single chamber or a plurality of chambers of the manufacturing apparatus, which will be described below in further detail with reference to FIGS. **13** to **14B**.

FIG. **13** is a schematic diagram of a manufacturing apparatus used to manufacture a semiconductor device according to example embodiments.

Referring to FIG. **13**, an apparatus **1** for manufacturing a semiconductor device may include a process chamber **1100**, a substrate support unit **1110** disposed in the process chamber **1100**, and a gas injection unit **1200** disposed in the process chamber **1100**, a gas supply unit **1300** connected to the gas injection unit **1200**, power supply units **1400** and **1450** connected to the substrate support unit **1110** and the gas injection unit **1200** respectively, an exhaust unit **1500** connected to the inside of the process chamber **1100**, and a control unit **1600**.

The apparatus **1** may be an apparatus for depositing and etching a thin film on a substrate SUB and may perform not only a CVD process or an ALD process but also a dry etching process. In particular, the apparatus **1** may be used to form the gate electrode **130** of the semiconductor devices of FIGS. **1** to **9**. The substrate SUB, processed by the apparatus **1**, may be provided on the substrate support unit **1110**.

The process chamber **1100** may provide a space in which a deposition process is performed. The process chamber **1100** may include an upper wall, a sidewall, and a lower wall. Although not illustrated, a passage, through which the substrate SUB is carried in or carried out, may be provided on one side of the process chamber **1100**.

The substrate support unit **1110** may be disposed in a lower region of the process chamber **1100**. The substrate support unit **1110** may include a support portion having an upper surface, on which the substrate SUB is seated, and an electrode **1150** in the support portion. The electrode **1150** may be supplied with, for example, radio-frequency (RF) power from the power supply unit **1400**.

The gas injection unit **1200** may be disposed above the substrate support unit **1110** to face the substrate support unit **1110** in the process chamber **1100**. The gas injection unit **1200** may be connected to the gas supply unit **1300** to distribute process gases, such as a source gas, a reactant gas, and an etching gas, supplied from the gas supply unit **1300** and to provide the distributed gases to the upper surface of the substrate SUB. The gas injection unit **1200** may be, for example, a shower head and may include a gas supply passage connected to first to fourth gas sources **1310**, **1320**, **1330**, and **1340** of the gas supply unit **1300**. In addition, the gas injection unit **1200** may include a plate **1220** having a plurality of injection holes PH for injecting a process gas.

The injection holes PH may be disposed radially from a central region of the gas injection unit **1200**. The gas injection unit **1200** may further include an electrode **1250** on the plate **1220**, and the electrode **1250** may be supplied with, for example, RF power from the power supply unit **1450**. In example embodiments, a diffusion plate may be further disposed in the gas injection unit **1200** to disperse the process gas.

The gas supply unit **1300** may include the first to fourth gas sources **1310**, **1320**, **1330**, and **1340** and first to fourth gas sources **1310**, **1320**, **1330**, and **1340** may be configured to supply different gases. For example, the source gas described with reference to FIG. **12** may be supplied through the first gas source **1310**, and the reactant gas may be supplied through the second gas source **1320**. In addition, the etching gas may be supplied through the third gas source **1330**, and the purge gas may be supplied through the fourth gas source **1340**. In some embodiments, the gas supply unit **1300** may include only three gas sources. For example, when an etching process is performed using the source gas used during a deposition process, in other words, when the deposition gas and the etching gas are the same, the third gas source **1330** may be omitted in the gas supply unit **1300**. The gas supply unit **1300** may include a mass flow controller (MFC) configured to control a supply flow rate, a valve configured to supply a gas to the process chamber **1100** or to cut off the supplied gas, or the like, other than the first to fourth gas sources **1310**, **1320**, **1330**, and **1340**.

The power supply units **1400** and **1450** may supply RF power and may generate an electric field, by a voltage difference, in lower and upper portions of the substrate SUB. Thus, plasma may be generated in a process region in which a deposition process is performed on the substrate SUB. The gas injection unit **1200** may be connected to a ground voltage by the power supply unit **1450**. The process region may correspond to a region between the substrate support unit **1110** and the gas injection unit **1200**. In example embodiments, since at least a portion of the source gas may be in a plasma state, deposition on the substrate SUB may be facilitated. However, the plasma may be controlled so as not to be generated in the etching process.

The exhaust unit **1500** may be configured to discharge by-products and residual gases in the process chamber **1100** to the outside of the process chamber **100**. The exhaust unit **1500** may include a vacuum pump. The materials inside the process chamber **1100** may be discharged to the outside of the process chamber **1100** by vacuum suction force generated by the vacuum pump. In example embodiments, a position, the number, and the like of the exhaust unit **1500** may be variously changed.

The controller **1600** may control gas supply order, time, flow rate, and the like of gases supplied by the gas supply unit **1300**. As described above with reference to FIG. **12**, the first gas source **1310** and the second gas source **1320** may be controlled to alternately supply the source gas and the reactant gas in the first and second deposition processes, and the third gas source **1330** may be controlled to supply the etching gas in the etching process. In addition, the gas supply unit **1300** may be controlled to sequentially perform the first deposition process, the etching process, and the second deposition process. As a result, the first deposition process, the etching process, and the second deposition process may be performed in-situ in the single process chamber **1100**. In this case, movement of the substrate SUB between chambers may be omitted to reduce a process time and to increase productivity. In addition, the controller **1600** may also control supply of the RF power supplied by the

power supply units **1400** and **1450**. Although not illustrated, the controller may include one or more of the following components: at least one central processing unit (CPU) configured to execute computer program instructions to perform various processes and methods, random access memory (RAM) and read only memory (ROM) configured to access and store data and information and computer program instructions, input/output (I/O) devices configured to provide input and/or output to the processing controller **1020** (e.g., keyboard, mouse, display, speakers, printers, modems, network cards, etc.), and storage media or other suitable type of memory (e.g., such as, for example, RAM, ROM, programmable read-only memory (PROM), erasable programmable read-only memory (EPROM), electrically erasable programmable read-only memory (EEPROM), magnetic disks, optical disks, floppy disks, hard disks, removable cartridges, flash drives, any type of tangible and non-transitory storage medium) where data and/or instructions can be stored. In addition, the controller can include antennas, network interfaces that provide wireless and/or wire line digital and/or analog interface to one or more networks over one or more network connections (not shown), a power source that provides an appropriate alternating current (AC) or direct current (DC) to power one or more components of the controller, and a bus that allows communication among the various disclosed components of the controller.

However, configurations, structures, and dispositions of the process chamber **1100**, the gas injection unit **1200**, the substrate support unit **1110**, the gas supply unit **1300**, the power supply unit **1400**, **1450** of the apparatus **1**, illustrated in FIG. **13**, are merely exemplary and may vary depending on example embodiments.

FIGS. **14A** and **14B** are schematic diagrams of a manufacturing apparatus used to manufacture a semiconductor device according to example embodiments.

Referring to FIG. **14A**, a manufacturing apparatus **2A** may include two chambers including first and second process chambers **1620** and **1640**, in which different processes are performed, and may further include a rotation driver **1700** connected to the first and second process chambers **1620** and **1640**, and a loadlock chamber **1800** disposed on one side of the rotation driver **1700**.

The first process chamber **1620** may be a chamber for deposition, and the second process chamber **1640** may be a chamber for performing an etching process. The first deposition process to form the preliminary first conductive layer **130AP** and the second deposition process to form the preliminary second conductive layer **130BP**, described above with reference to FIG. **12**, may be performed in the first process chamber **1620**. The etching process to etch the preliminary first conductive layer **130AP** and the preliminary second conductive layer **130BP**, described above with reference to FIG. **12**, may be performed in the second process chamber **1640**. Each of the first and second process chambers **1620** and **1640** may have the same or similar structure as described above with reference to FIG. **13**.

The rotation driver **1700** may be connected to the first and second process chambers **1620** and **1640**. The rotation driver **1700** may drive an arm portion **1750** to elevate the substrate **SUB** (see FIG. **13**), and may rotate the arm portion **1750** to move the substrate **SUB** between the first and second process chambers **1620** and **1640**.

The loadlock chamber **1800** may be provided to protect the first and second process chambers **1620** and **1640** from an external environment, and may include a loading portion and an unloading portion. For example, the loadlock cham-

ber **1800** may allow introduction of a new wafer into the rotation driver **1700** with little breaking of vacuum therein.

Referring to FIG. **14B**, a manufacturing apparatus **2B** may include three process chambers including first to third process chambers **1620**, **1640**, and **1660**, in which different processes are performed, and may further include a rotation driver **1700** connected to the process chambers **1620**, **1640**, and **1660**, and a loadlock chamber **1800** disposed on one side of the rotation driver **1700**.

The first and third process chambers **1620** and **1660** may be a chamber for deposition, and the second process chamber **1640** may be a chamber for performing an etching process. The first deposition process to form the preliminary first conductive layer **130AP**, described above with reference to FIG. **12**, may be performed in the first process chamber **1620**, and the etching process to etch the preliminary first conductive layer **130AP**, described above with reference to FIG. **12**, may be performed in the second process chamber **1640**. The second deposition process to form the preliminary second conductive layer **130BP**, described above with reference to FIG. **12**, may be performed in the third process chamber **1660**. Each of the first and third process chambers **1620**, **1640**, and **1660** may have the same or similar structure as described above with reference to FIG. **13**.

When the semiconductor devices, described above with reference to FIGS. **1** to **9**, are manufactured using a system in-situ apparatus such as the manufacturing apparatuses **2A** and **2B** of FIGS. **14A** and **14B**, the first deposition process to form the preliminary first conductive layer **130AP**, the etching process to etch the preliminary first conductive layer **130AP**, and the second deposition process to form the preliminary second conductive layer **130BP**, described above with reference to FIG. **12**, may be performed in the same apparatus and at least portions of the processes may be performed in different process chambers **1620**, **1640**, and **1660**. In this case, a chamber, in which the deposition process is performed, and a chamber, in which the etching process is performed, may be separated to be advantageous for process control such as each etching rate control thereof.

As described above, gate electrodes may be formed to include first and second conductive layers having an interface, a sloped surface, in an edge region. Thus, a semiconductor device having increased reliability may be provided. In addition, an apparatus for efficiently manufacturing such a semiconductor device may be provided.

While example embodiments have been shown and described above, it will be apparent to those skilled in the art that modifications and variations could be made without departing from the scope of the present inventive concept as defined by the appended claims.

What is claimed is:

1. A method for manufacturing a semiconductor device, comprising:

forming a stacked structure by alternately stacking a plurality of insulating layers and a plurality of sacrificial layers on a substrate;

forming a plurality of channel structures by penetrating the stacked structure;

forming a plurality of separation regions by penetrating the stacked structure;

forming a plurality of lateral openings by removing the plurality of sacrificial layers exposed through the plurality of separation regions;

forming a preliminary first conductive layer in the plurality of lateral openings;

forming a plurality of first conductive layers by removing portions of the preliminary first conductive layer such

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- that in a first region adjacent to the plurality of separation regions, each of the plurality of first conductive layers has a decreasing thickness toward the plurality of separation regions; and
forming a plurality of second conductive layers on the plurality of first conductive layers to form a plurality of gate electrodes,
wherein in the forming of the plurality of first conductive layers, the portions of the preliminary first conductive layer are removed by a dry etching process, and a source gas used in the forming of the preliminary first conductive layer is used as an etching gas in the dry etching process.
2. The method of claim 1, wherein in the forming of the plurality of first conductive layers, only the source gas is introduced without a reactant gas.
3. The method of claim 1, wherein the source gas includes at least one of WF_6 , WCl_6 , WCl_5 , $W(CO)_6$, $W(C_6H_6)_2$, $W(PF_3)_6$, $W(allyl)_4$, and $(1, 5-COD)W(CO)_4$, $(C_5H_5)_2WH_2$.
4. The method of claim 1, wherein each of the plurality of second conductive layers has an increasing thickness toward the plurality of separation regions in the first region.
5. The method of claim 1, wherein the first region is between an outermost one of the plurality of channel structures and one of the plurality of separation regions.
6. The method of claim 1, wherein the forming of the preliminary first conductive layer includes:
forming a first nucleation layer in the plurality of lateral openings; and
forming a first bulk layer on the first nucleation layer.
7. The method of claim 6, wherein the first nucleation layer has an amorphous structure, and the first bulk layer has a crystalline structure.
8. The method of claim 1, wherein an interface between each of the plurality of first conductive layers and each of the plurality of second conductive layers is sloped with respect to an upper surface of the substrate in the first region.
9. The method of claim 8, wherein the interface between each of the plurality of first conductive layers and each of the plurality of second conductive layers is substantially parallel to the upper surface of the substrate in a second region, between two adjacent channel structures of the plurality of channel structures.
10. The method of claim 1, wherein the forming of the plurality of second conductive layers includes:
forming a preliminary second conductive layer on the plurality of first conductive layers; and
forming the plurality of second conductive layers by removing portions of the preliminary second conductive layer such that the plurality of second conductive layers are disposed only in the plurality of lateral openings.
11. The method of claim 10, wherein the forming of the preliminary second conductive layer includes:
forming a second nucleation layer on the plurality of first conductive layers; and
forming a second bulk layer on the second nucleation layer.
12. A method for manufacturing a semiconductor device, comprising:
forming a stacked structure by alternately stacking a plurality of insulating layers and a plurality of sacrificial layers on a substrate;
forming a plurality of channel structures by penetrating the stacked structure;
forming a separation region by penetrating the stacked structure;

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- forming a plurality of lateral openings by removing the plurality of sacrificial layers exposed through the separation region;
forming a preliminary first conductive layer in the plurality of lateral openings;
forming a plurality of first conductive layers by removing portions of the preliminary first conductive layer such that in a first region adjacent to the separation region, each of the plurality of first conductive layers has a decreasing thickness toward the separation region; and
forming a plurality of second conductive layers on the plurality of first conductive layers to form a plurality of gate electrodes,
wherein the forming of the preliminary first conductive layer includes:
forming a nucleation layer in the plurality of lateral openings; and
forming a bulk layer on the nucleation layer.
13. The method of claim 12, wherein in the forming of the preliminary first conductive layer, a first source gas is introduced to deposit the preliminary first conductive layer, and
in the forming of the plurality of first conductive layers, the portions of the preliminary first conductive layer are removed by a dry etching process using the first source gas as an etching gas.
14. The method of claim 13, wherein in the forming of the plurality of first conductive layers, only the first source gas is introduced without a reactant gas.
15. The method of claim 13, wherein the first source gas includes at least one of WF_6 , WCl_6 , WCl_5 , $W(CO)_6$, $W(C_6H_6)_2$, $W(PF_3)_6$, $W(allyl)_4$, and $(1, 5-COD)W(CO)_4$, $(C_5H_5)_2WH_2$.
16. The method of claim 13, wherein in the forming of the preliminary first conductive layer, a reactant gas is further introduced to deposit the preliminary first conductive layer.
17. The method of claim 12, wherein in the first region, each of the plurality of first conductive layers has a first portion which contacts a sidewall of an outermost channel structure of the plurality of channel structures and vertically extends along the sidewall thereof, and a second portion connected to the first portion and extending horizontally from the first portion toward the separation region, and a thickness of the second portion decreasing from where the second portion and the first portion are connected to each other toward the separation region, and a thickness of each of the plurality of the second conductive layers increasing from where the second portion and the first portion are connected to each other toward the separation region.
18. A method for manufacturing a semiconductor device, comprising:
forming a stacked structure by alternately stacking a plurality of insulating layers and a plurality of sacrificial layers on a substrate;
forming a plurality of channel structures by penetrating the stacked structure;
forming a plurality of separation regions by penetrating the stacked structure;
forming a plurality of lateral openings by removing the plurality of sacrificial layers exposed through the plurality of separation regions;
forming a preliminary first conductive layer in the plurality of lateral openings using a first source gas;
forming a plurality of first conductive layers by removing portions of the preliminary first conductive layer using the first source gas as an etching gas; and

forming a plurality of second conductive layers on the plurality of first conductive layers to form a plurality of gate electrodes.

19. The method of claim **18**, wherein in the forming of the plurality of first conductive layers, only the first source gas 5 is introduced without a reactant gas.

20. The method of claim **18**, wherein the forming of the plurality of second conductive layers includes:
forming a nucleation layer on the plurality of first conductive layers; and 10
forming a bulk layer on the nucleation layer.

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